

**UNITED STATES PATENT AND TRADEMARK OFFICE**

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**BEFORE THE PATENT TRIAL AND APPEAL BOARD**

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**BOE Technology Group Co., Ltd.  
Petitioner**

**v.**

**Optronic Sciences LLC  
Patent Owner**

**Inter Partes Review No.: IPR2025-00238**

**PETITION FOR INTER PARTES REVIEW OF U.S. PATENT NO.  
8,604,471 UNDER 35 U.S.C. §§ 311-319 AND 37 C.F.R. §§ 42.1-100, ET SEQ**

U.S. Patent No. 8,604,471  
Petition for *Inter Partes* Review

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Exhibit No.	Description
1001	U.S. Pat. No. 8,604,471 (“ <b>the 471 Patent</b> ”)
1002	Declaration of Dr. R. Jacob Baker
1003	File History of 8,604,471 (13/208,360)
1004	U.S. 2008/0158108 (“ <b>Hwang</b> ”)
1005	U.S. 2010/0148175 (“ <b>Godó</b> ”)
1006	U.S. 2009/0184898 (“ <b>Yamashita</b> ”)
1007	Solid State Electronic Devices 4 <sup>th</sup> Edition by Ben Streetman
1008	Handbook of Optics 2 <sup>nd</sup> Edition Volume II by Michael Bass et al.
1009	KR 10-0853543B1
1010	Certified translation of KR 10-0853543B1
1011	KR 10-0659756B1
1012	Certified translation of KR 10-0659756B1
1013	Introduction to VLSI Systems by Carver Mead and Lynn Conway
1014	Schaum’s Outline of Theory and Problems of Basic Circuit Analysis 2 <sup>nd</sup> Edition by John O’Malley
1015	U.S. Pat. No. 5,838,399
1016	Curriculum Vitae of Dr. R. Jacob Baker
1017	Initial Infringement Contentions for U.S. Patent No. 8,604,471
1018	February 14, 2025 District Court Docket Control Order
1019	Judge Gilstrap Jury Trial Setting Docket Report

<b>CHART OF CLAIMS</b>
[1pre] A semiconductor structure, disposed on a substrate, and comprising:
[1a] a gate electrode, disposed on the substrate;
[1b] a gate insulating layer, disposed on the substrate, and covering the gate electrode;
[1c] a channel layer, disposed on the gate insulating layer and located above the gate electrode, wherein the channel layer has a channel length L along a channel direction and has a first side and a second side opposite to the first side;
[1d] a source electrode and a drain electrode, located at the two opposite sides of the channel layer, and electrically connected to the first side and the second side of the channel layer, respectively;
[1e] a dielectric layer, covering the source electrode, the drain electrode and the channel layer; and
[1f] a conductive light-shielding pattern layer, disposed on the dielectric layer, and overlapped to a portion of the source electrode and a portion of the channel layer in a vertical projection, wherein the conductive light-shielding pattern layer does not overlap to the drain in the vertical projection, and the conductive light-shielding pattern layer and the channel layer have an overlapping length d1, and $0.3 \leq d1/L \leq 0.85$ .
[4] The semiconductor structure as claimed in claim 1, wherein the conductive light-shielding pattern layer has a third side and a fourth side along the channel direction, the fourth side is overlapped to the channel layer in the vertical projection, wherein the overlapping length d1 is equal to a distance between the fourth side and the first side of the channel layer along the channel direction.
[6] The semiconductor structure as claimed in claim 1, wherein the source electrode and the drain electrode respectively cover a portion of the channel layer.
[9pre] An organic electroluminescence device, disposed on a substrate, and comprising:
[9a] a gate electrode, disposed on the substrate;
[9b] a gate insulating layer, disposed on the substrate, and covering the gate electrode;
[9c] a channel layer, disposed on the gate insulating layer and located above the gate electrode, wherein the channel layer has a channel length L along a channel direction and has a first side and a second side opposite to the first side;
[9d] a source electrode and a drain electrode, located at the two opposite sides of the channel layer, and electrically connected to the first side and the second side of the channel layer, respectively;

**CHART OF CLAIMS**

[9e] a dielectric layer, covering the source electrode, the drain electrode and the channel layer;
[9f] a conductive light-shielding pattern layer, disposed on the dielectric layer, and overlapped to a portion of the source electrode and a portion of the channel layer in a vertical projection, wherein the conductive light-shielding pattern layer does not overlap to the drain in the vertical projection, and the conductive light-shielding pattern layer and the channel layer have an overlapping length $d_1$ , and $0.3 \leq d_1/L \leq 0.85$ ;
[9g] a lower electrode, disposed on the dielectric layer and electrically connected to the drain electrode;
[9h] an organic light emitting layer, disposed on the lower electrode; and
[9i] an upper electrode, disposed on the organic light emitting layer.
[12] The organic electroluminescence device as claimed in claim 9, wherein the conductive light-shielding pattern layer has a third side and a fourth side along the channel direction, the fourth side is overlapped to the channel layer in the vertical projection, wherein the overlapping length $d_1$ is equal to a distance between the fourth side and the first side of the channel layer along the channel direction.
[14] The organic electroluminescence device as claimed in claim 9, wherein the source electrode and the drain electrode respectively cover a portion of the channel layer.
[17] The semiconductor structure as claimed in claim 1, wherein the conductive light-shielding pattern layer and the drain electrode are spaced by a distance along the channel direction in the vertical projection.
[18] The organic electroluminescence device as claimed in claim 9, wherein the conductive light-shielding pattern layer and the drain electrode are spaced by a distance along the channel direction in the vertical projection.



## I. INTRODUCTION

BOE Technology Group Co. LTD. (“Petitioner”) requests inter partes review of claims 1, 4, 6, 9, 12, 14, 17, and 18 (“Challenged Claims”) of U.S. Patent No. 8,604,471 (“471 patent,” EX1001), owned by Optronic Sciences LLC (“PO”).

This petition relies upon the declaration of Dr. R. Jacob Baker (EX1002) and copies large portions of that declaration herein.

In accordance with 37 C.F.R. §42.104(a), Petitioner certifies that the 471 patent is available for *inter partes* review and that Petitioner is not barred or estopped from requesting an *inter partes* review challenging the patent claims on the grounds identified in this Petition.

## II. STATEMENT OF PRECISE RELIEF REQUESTED

In accordance with 35 U.S.C. § 311, Petitioner requests cancelation of claims 1, 4, 6, 9, 12, 14, 17, and 18 of the 471 patent in view of the following grounds:

Ground	Claims	Basis	Prior Art
1	1, 4, 6, 9, 12, 14, 17, 18	§103	Hwang
2	Same	§103	Hwang and Godo
3	Same	§103	Hwang and Yamashita
4	Same	§103	Hwang, Godo and Yamashita

### III. THE 471 PATENT

#### A. Overview of the 471 Patent

The 471 patent was filed on August 12, 2011, claiming priority to a foreign application filed on May 24, 2011, and issued on December 10, 2013. EX1001, Face of Patent. EX1002, ¶44.

The 471 patent purports to improve the quality of a display by utilizing a light-shielding layer which overlaps channel layer of a thin film transistor to reduce the adverse effects of light irradiation including drain induced barrier lowering (DIBL) and associated current leakages. EX1001, 1:33-39, 3:8-21, 6:29-51. EX1002, ¶45.

The 471 patent discloses a semiconductor structure as shown in the embodiments in Figs. 1A-4B. Exemplary Figure 4A includes the components as follows: a substrate (12), channel layer (430), gate insulating layer, gate electrode, source electrode (440), drain electrode (450), dielectric layer, and conductive light-shielding pattern layer.

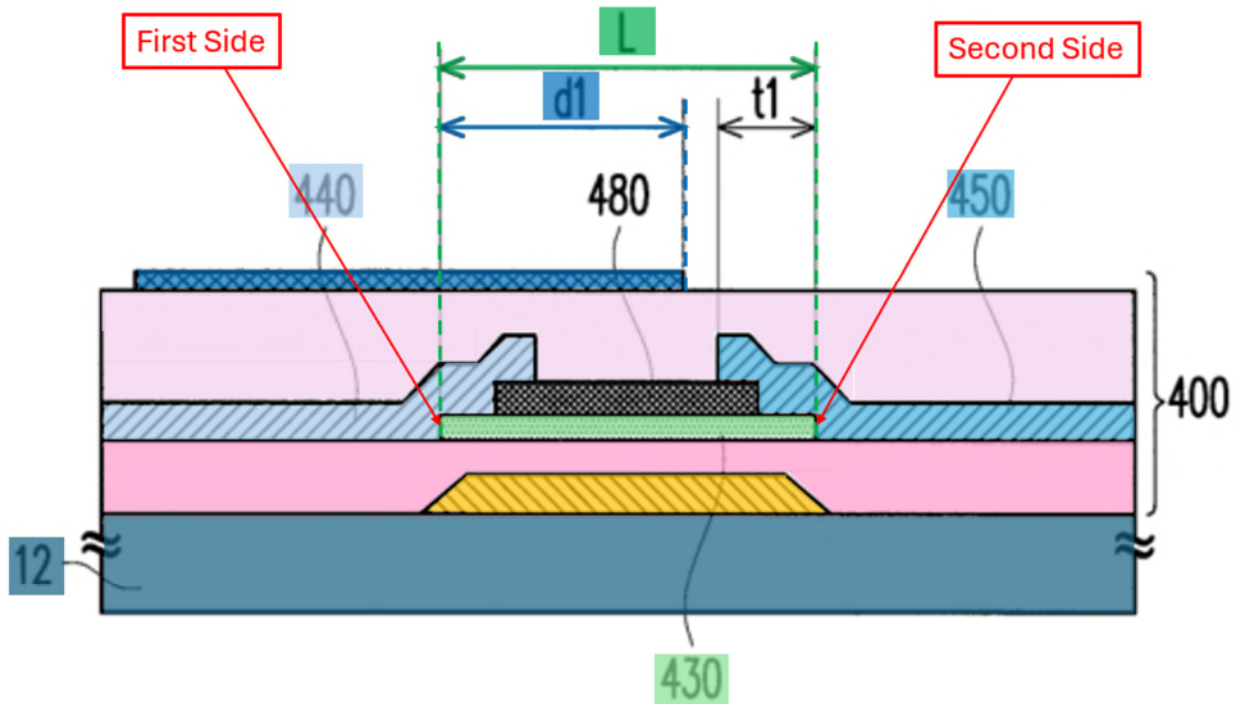


FIG. 4A

EX1001, Fig. 4A, 4:06-23, 5:55-6:07. EX1002, ¶46.

The purported key innovation is reducing the DIBL effect by including a **conductive light-shielding pattern layer** that overlaps, in part, a **channel layer**.

EX1001, Fig. 5A-5B, 6:22-39. The 471 patent defines the length “L” of the channel layer and the length “d1” of the overlapping portion of the conductive light-shielding pattern layer as shown Fig. 4A, and claim a range of overlap based on  $d1/L$ . EX1001, 4:06-23, 5:31-34, 5:46-50, 6:22-39, claims [1f], 4, [9f], 12. As used in the 471 patent, the “channel layer” includes the portions of the layer that

are above (or under) the source and drain electrodes (e.g., length  $t_1$ ). *See, e.g.*, EX1001, Figs. 1A, 3A, 4A, and claims 5, 6, 8. Thus, the “channel layer” is not limited to only the channel region of the thin film transistor. The structures of the disclosed and claimed embodiments are discussed in more detail below with respect to claim construction. EX1002, ¶47.

### **B. Overview of the 471 patent’s File History**

The 471 patent was filed as Appl. No. 13/208,360 on August 12, 2011. EX1001, Face of Patent.

On Mar. 29, 2013, the examiner rejected all claims in the original application. EX1003, 46-53. The examiner rejected claims 1 and 4 over Song et al. (2008/02783435) in view of Egami (2011/0215337) in view of Mori (2011/0198607), stating it would have been obvious to a POSITA to “include the required relationship among light shield, channel, source and drain...in order to have a semiconductor device with low leakage.” EX1003, 47-48. The examiner rejected claims 9 and 12, over Song in view of Kwak (2007/1076554) in view of Mori with the same reasoning. EX1003, 50-51.

On June 28, 2013, the applicant amended exemplary claim [1f] as follows:

a conductive light-shielding pattern layer, disposed on the dielectric layer, and overlapped to a portion of the source electrode and a portion of the channel layer in a vertical projection, wherein the conductive light-shielding pattern layer

does not overlap to the drain in the vertical projection, and the  
conductive light-shielding pattern layer and channel layer have  
an overlapping length  $d_1$ , and  $0.3 \leq d_1/L \leq 0.85$ .

EX1003, 30, 32, 35-40.

On Sept. 16, 2013, the examiner allowed the amended claims only because the “prior art failed to establish the amended conductive light shielding pattern that does not overlap [sic] with the drain electrode.” EX1003, 13. The claims issued on December 10, 2013. EX1001, Face of Patent. The prior art asserted herein discloses the limitation that was the basis for allowance (and all the others) as shown below. EX1002, ¶¶48-51.

### **C. Person of Ordinary Skill in the Art**

A person of ordinary skill in the art at the time of the alleged invention of the 471 patent (the earliest claimed priority date of May 24, 2011) (“POSITA”) would have had a Bachelor’s degree in electrical or computer engineering or a comparable field of study, plus approximately two to three years of professional experience with integrated circuit layout or other relevant industry experience. Additional graduate education could substitute for professional experience, and significant experience in the field could substitute for formal education. EX1002, ¶52.

#### **IV. CLAIM CONSTRUCTION UNDER 37 C.F.R. § 42.104(B)(3)**

The Challenged Claims are interpreted using the same claim construction standard that is used to construe the claim in a civil action in federal district court. 37 C.F.R. § 42.100(b).

Because the prior art asserted herein discloses the preferred embodiment within the indisputable scope of the claims, the Board need not construe the outer bounds of the claims as part of these proceedings. *See, e.g., Nidec Motor Corp. v. Zhongshan Broad Ocean Motor Co.*, 868 F.3d 1013, 1017 (Fed. Cir. 2017).

Any claim terms not listed below should be construed according to their plain and ordinary meaning to a POSITA at the time of the 471 patent.

##### **1. “a conductive light-shielding pattern layer”**

###### **a. Primary Construction**

This term is entitled to its ordinary meaning, which is not limited to any particular degree of conduction or light-shielding. For example, there is no claimed minimum level of electrical conductivity or percent optical opacity. The prior art applied herein discloses (or at last renders obvious) a significant amount of conductivity and light-shielding. Thus, it is not necessary for the Board to construe the outer bounds of these limitations. EX1002, ¶56.

As for “conductive,” the specification states several times that the pattern layer is “conductive” and makes clear that “conductive” refers to electrical conductivity. EX1001, 4:40-5:9 (disclosing the conductive light-shielding pattern

is made from the same metal material as the lower electrode of the LED device).

But the amount of conductivity is not discussed in the specification. Thus, there is no definition or disclaimer that could properly limit the claim. Nor is there a disclosed level of conductivity that could improperly be read into the claim.

EX1002, ¶57.

As for “light-shielding,” the specification describes that the pattern layer “can mitigate the DIBL effect, and shield a certain amount of the light (for example, an ultraviolet (UV) light) in the light irradiation step to reduce the influence on the channel layer 130 caused by the light irradiation.” EX1001, 4:6-24. The “irradiation step” is performed during packaging. *Id.*, 1:29-33. The ordinary meaning of this limitation is not limited to a) the intended purpose of mitigating the DIBL effect, b) the intended (and indefinite) “certain amount” of light shielding, c) the intended type of light-shielding (UV irradiation during packaging), or d) the intended shielded object (the channel layer). This limitation does not recite those limitations and there is no disclaimer or definition that could properly limit this limitation to those purposes. EX1002, ¶58.

These intended purposes should not be read into the claim for the usual reason that it is improper to do so. *See, e.g.*, Paper 39 (Final Written Decision) *Home Depot USA, Inc. v. Lynk Labs, Inc.* IPR2021-01541, at 16-17 (refusing to read in “light enhancing” or any degree of reflectivity into the limitation “reflective

substrate”); Paper 40 (Final Written Decision) *Home Depot USA, Inc. v. Lynk Labs, Inc.* IPR2022-00023, at 12-14 (“Neither Claim 1 nor any of the dependent claims 2–4 require that the “reflective material” reflect any minimum amount of light.”)

Here, would be improper to read in a “certain amount” of light-shielding for the additional reason that the specification does not disclose what the “certain amount” is, so reading in a “certain amount” would render the claims indefinite. EX1002, ¶60.

The intrinsic record is clear that the claims merely recite the physical arrangement of a conductive light-shielding pattern relative to certain other claimed components. As long as the claimed physical arrangement is satisfied, and as long as the pattern layer has some amount of conductivity and light-shielding, nothing else is required by the ordinary meaning of the claim. EX1002, ¶61.

The only other guidance in the specification is that a layer made of “metal” in the claimed physical arrangement is an example of a conductive light-shielding pattern layer. EX1001, 3:58-61, 4:40-5:9. Accordingly, a POSITA would have understood that a metal layer which satisfies the claimed physical arrangement to be within the scope of this limitation. EX1002, ¶62.



**b. Alternative Construction**

In the alternative, this term could be construed to mean “a layer that the designer subjectively intends to serve the purpose of being electrically conductive and shielding the channel layer from some light.” Petitioner offers this alternative construction out of an abundance of caution in case PO attempts to argue that some aspects of the specification should be read into the claim. EX1002, ¶63.

This construction reads in the unclaimed but disclosed intended purpose of shielding the channel layer from some light (which would result in some mitigation of the DIBL effect) and that the designer intend that purpose. This construction does not read in the intended wavelength of light (UV) or the intended step during which the light shielding occurs (during packaging). This construction also does not read in any degree of conductivity or light shielding, because there is no sufficiently definite teaching in the specification that could be read into the claim. EX1002, ¶64.

As explained below, in Grounds 1 and 2, it would have been inherent, or at least obvious, for Hwang’s metal layer 162a to perform the function of light-shielding. In Grounds 3 and 4, based on the teachings of Yamashita, it would have been obvious for the designer to intend that Hwang’s metal layer 162a serve that purpose. EX1002, ¶65.

## V. OVERVIEW OF THE PRIOR ART REFERENCES

### A. EX1004 – Hwang

US 2008/0158108 to Hwang et al. (“**Hwang**”) was published on July 3, 2008 and is prior art under at least Pre-AIA Section 102(b).

Hwang generally relates to OLED devices. EX1004, Abstract, [0002].

Hwang’s device architecture involves OLEDs arranged above drive transistors that are bottom-gate thin film transistors (“TFTs”). EX1004, [0014]-[0016], Figs. 6A-6D. Hwang addresses a problem in art where the current applied to the OLED element induces an electric field that affects the channel region of a drive transistor. *Id.* Hwang discloses a solution to the problem by including a metal shielding layer overlying the channel and source regions (but not the drain region) of the driver transistor underneath to shield them from the electric field generated by the LED. EX1004, [0017]-[0020], [0050], [0072], [0101]. By incorporating the shielding layer, the image quality of the overall luminescent display device is improved, such as by preventing brightness reduction or unintended brightness non-uniformity. EX1004, [0141]-[0142]. EX1002, ¶67.

### B. EX1005 – Godo

US 2010/0148175 to Godo et al. (“**Godo**”) was published on June 17, 2010, filed on Dec. 8, 2009, and is prior art under at least Pre-AIA Sections 102(a) and (e).

Godo generally relates to TFTs (including bottom gate transistors) used in LED display devices. EX1005, Abstract, [0001]-[0002], Figs. 18A/B. Godo addresses a problem with light leakage current in TFTs that arises when the semiconductor layer in the TFT is irradiated by incident light. EX1005, [0003]-[0005]. Godo discloses a solution to this problem is provide a metallic light-blocking material arranged to shield the channel region in the TFT from incident light. EX1005, [0006]-[0008], [0012], [0015]-[0016]; [0045]. By addressing the light leakage current, the performance of the display device can be improved with a high contrast ratio and low power consumption. EX1005, [0016]. Although suitable dimensions for TFTs to drive LED devices are generally well known in the art (as evidenced by the general lack of specificity in disclosed TFT dimensions in prior art patent documents, demonstrating that its express disclosure is unnecessary to provide an enabling disclosure), Godo provides some specific dimensions that would be suitable for bottom gate thin film drive transistors. EX1005, Figs. 20A/B. EX1002, ¶69.

**C. EX1006 – Yamashita**

US 2009/0184898 to Yamashita at el. (“Yamashita”) was published on July 23, 2009 and is prior art under at least Pre-AIA Section 102(b).

Yamashita also relates to electroluminescent display devices with TFT drive transistors. EX1006, Abstract, [0002]-[0009]. Yamashita addresses a problem

arising from light irradiation into the channel region of TFT's, namely, the shift in threshold voltage and carrier mobility that lead to unintended variations in the LED brightness. EX1006, [0012]-[0016], [0035]-[0038]. Yamashita teaches that the source of light irradiation on a TFT in one pixel can even originate from LED devices in adjacent pixels. EX1006, [0036]-[0037], Fig. 7. Similar to Godo, Yamashita also teaches to solve this problem by including a metallic light-shielding layer to prevent the internally scattered light from entering the channel region of the TFT and shifting the TFT threshold voltage. EX1006, [0046]-[0049], [0093]-[0100], Fig. 13. EX1002, ¶71.

#### **D. Analogous Art**

Each of Hwang, Godo, Yamashita and the other references discussed herein is analogous art to the 471 patent because each is related to semiconductor structures for a light emitting device. EX1001, 1:18-20. EX1002, ¶72.

### **VI. GROUND 1: HWANG**

#### **A. Hwang**

The determination of obviousness is always made from the perspective of a POSITA. As discussed below, the teachings of Hwang would have rendered the claims obvious in view of the knowledge of a POSITA.

#### **B. Knowledge of POSITA regarding light shielding**

As discussed below for limitation [1f]/[9f], the teachings of Hwang would have rendered the claims obvious in view of the knowledge of a POSITA.

The problems associated with light entering a channel region of a transistor and the adverse impacts on transistor performance are well-known and extensively documented in the prior art. Some exemplary references are summarized herein. Light can create electron-hole pairs (“EHPs”) in semiconductors and thus alter the density of charge carriers in the material. EX1007, 96-97, 103; *see generally* Chapter 4. These EHPs alter the electrical properties of the semiconductor (and thus the device), including *e.g.*, the threshold voltages in transistors and/or increase leakage current. These problems are especially acute for optoelectronic devices due to the presence of light generating elements integrated with, and in close proximity to, such transistors. EX1002, ¶75.

This problem is discussed in Yamashita. Yamashita relates to organic electroluminescent devices that incorporates transistor circuitry. EX1006, [0009]-[0010]. Yamashita addresses the known problem in the art when light enters the channel region of a transistor and causes a shift in the threshold voltage of the transistor. EX1006, [0036]-[0038]. Yamashita discloses that in such devices, light can enter a channel region of a transistor (even one located in an adjacent pixel) due to internal scattered light from repeated reflections. EX1006, [0035]-[0037], Fig. 7. Such shifts in the threshold voltage are undesirable in drive transistors for organic light emitting diodes (“OLEDs”) as they lead to unintended fluctuations in the drive current, and therefore fluctuations in the brightness of the OLED element.

EX1006, [0013]-[0015], [0038]-[0042], Figs. 8-9. Yamashita discloses a solution to this problem is to form a light-shielding layer that is arranged above the channel region of the TFT in order to shield it from light. EX1006, [0045]-[0048], [0052], [0095]-[0099] (disclosing “the light shield pattern 67 should preferably be so arranged as to cover the sampling transistor T1 as well as the entire channel layer of the driving transistor T2”), Fig. 13. Yamashita discloses that while any material that reduces the amount of scattered light entering the thin-film transistor would help address the problem, metal materials are superior. EX1006, [0048]-[0049], [0136]-[0137]. Yamashita further teaches that the metal light-shielding layer should be electrically connected to a constant potential line. EX1006, [0047], [0101]-[0103]. EX1002, ¶76.

Similarly, Godo discloses that it is well-known in the art that when semiconductor material (in a transistor of a display device) is irradiated with light, light leakage current will be generated due to the photovoltaic effect and deteriorates the display quality. EX1005, [0004]. Godo discloses that mitigation techniques such as shielding the semiconductor layer from light were known. *Id.*, [0004]-[0006]. Reducing the leakage current can be accomplished by shielding the semiconductor layer with a conductive electrode made with various metals and their alloys. *Id.*, [0012]; [0015]-[0016]; [0045]. EX1002, ¶77.

KR100853543 likewise discloses the use of a light-blocking film in an OLED display to stop light (external or from an adjacent pixel) from entering the semiconductor layer of a TFT to ensure stable driving properties for the transistor. EX1010, Abstract, <9>, <16>, <38>, <39>. KR100853543 explains that this light can generate a photocurrent in the semiconductor layer and adversely impact the driving properties of the TFT. EX1010, <15>. EX1002, ¶78.

KR100659756 is yet another reference that discloses the problem with light entering the semiconductor layer of a TFT, particularly those with a bottom-gate structure. EX1012, 5. KR100659756 discloses to use one or more metals (including aluminum and molybdenum that are good light reflectors and good electrical conductors) as suitable materials for forming a light-blocking film to prevent both external light as well as internally generated light (*e.g.* from the OLED) from causing a negative effect on the TFT. EX1012, 7. EX1002, ¶79.

**C. Claim 1**

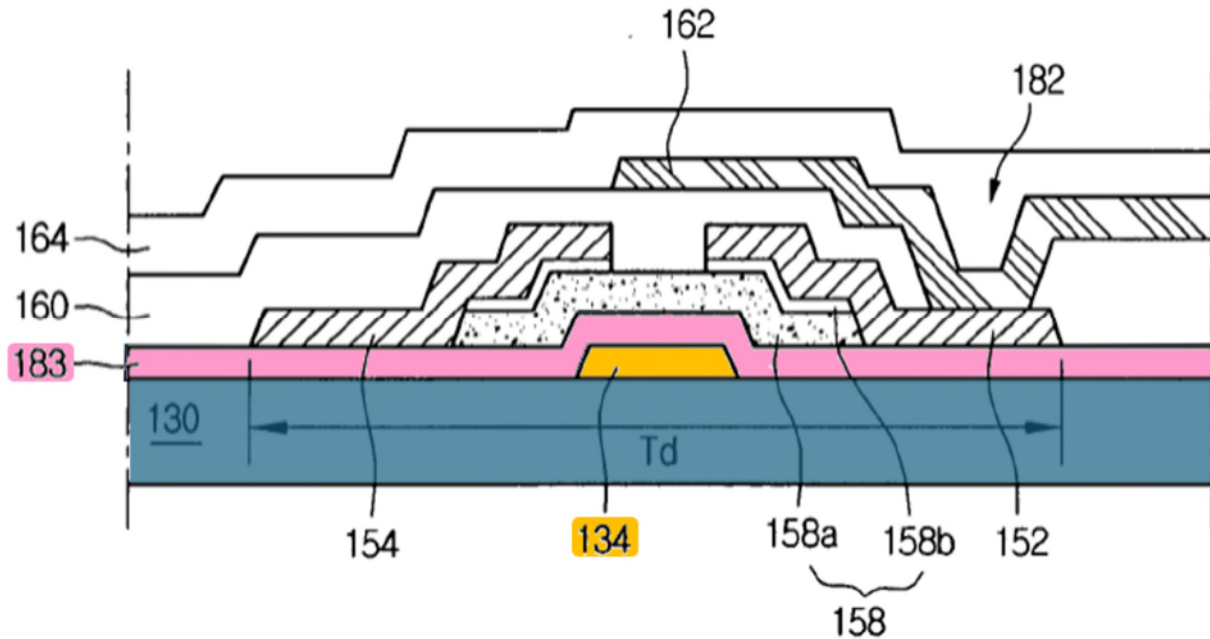
- 1. [1pre] A semiconductor structure, disposed on a substrate, and comprising:**

Hwang discloses “a semiconductor structure (a transistor, **Td**, driving an OLED), disposed on a [substrate \(130\)](#), and comprising (see claim1).”





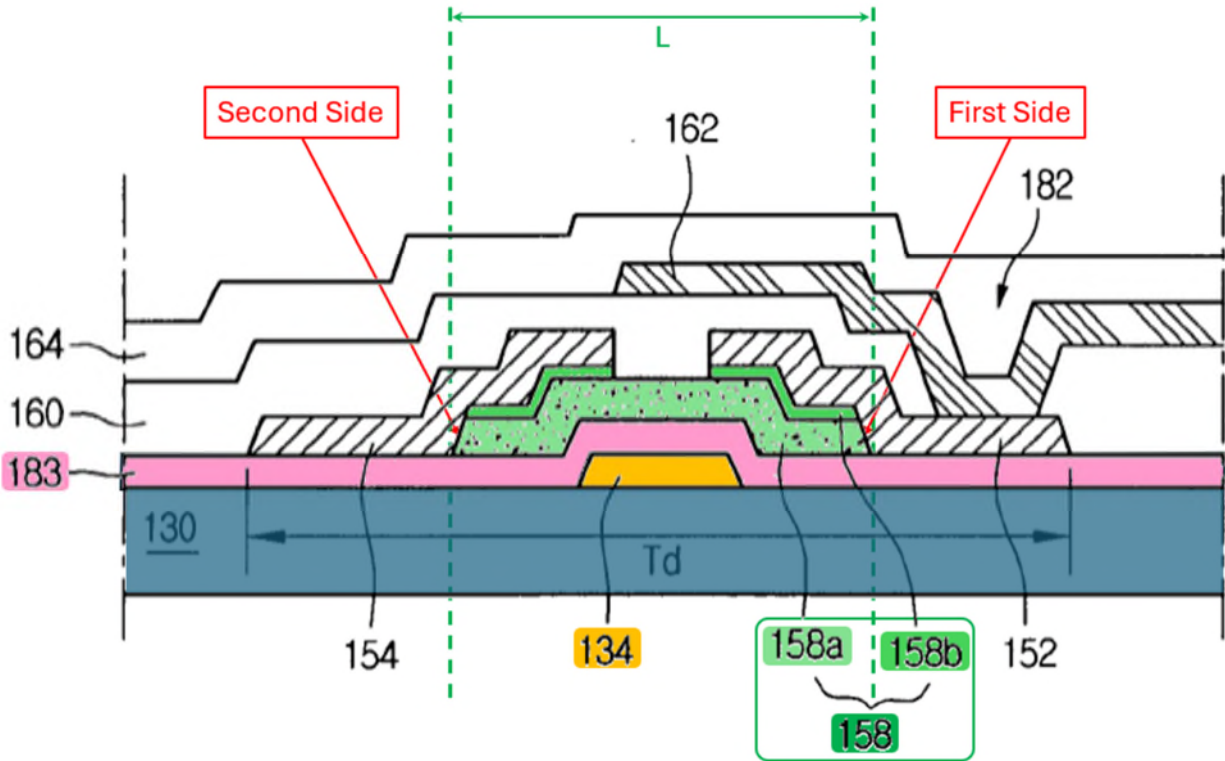




EX1004, Fig. 6c (gate insulating layer annotated in pink). Hwang discloses depositing an insulating material over the entire surface of the substrate (including the previously-formed gate electrode) to form the gate insulating layer. EX1004, [0077]. EX1002, ¶¶84-85.

4. [1c] a channel layer, disposed on the gate insulating layer and located above the gate electrode, wherein the channel layer has a channel length  $L$  along a channel direction and has a first side and a second side opposite to the first side;

Hwang discloses “a channel layer (158), disposed on the gate insulating layer (183) and located above the gate electrode (134), wherein the channel layer has a channel length  $L$  along a channel direction and has a first side and a second side opposite to the first side.”



EX1004, Fig. 6c (channel layer annotated in green). Hwang discloses patterning amorphous silicon layers deposited on the gate insulating layer to form active layer 158a and ohmic contact layer 158b. EX1004, [0078]. A POSITA would have understood that the claimed “channel layer” to include at least layer 158a that serves as the active semiconductor layer for the drive transistor, with the first and second sides as annotated. Further, the source of the drive transistor is on the right and the drain is on the left (EX1004, [0078]-[0080]), and thus a POSITA would have recognized that the channel layer has a channel length “L” along the channel direction as annotated. EX1002, ¶¶86-87.

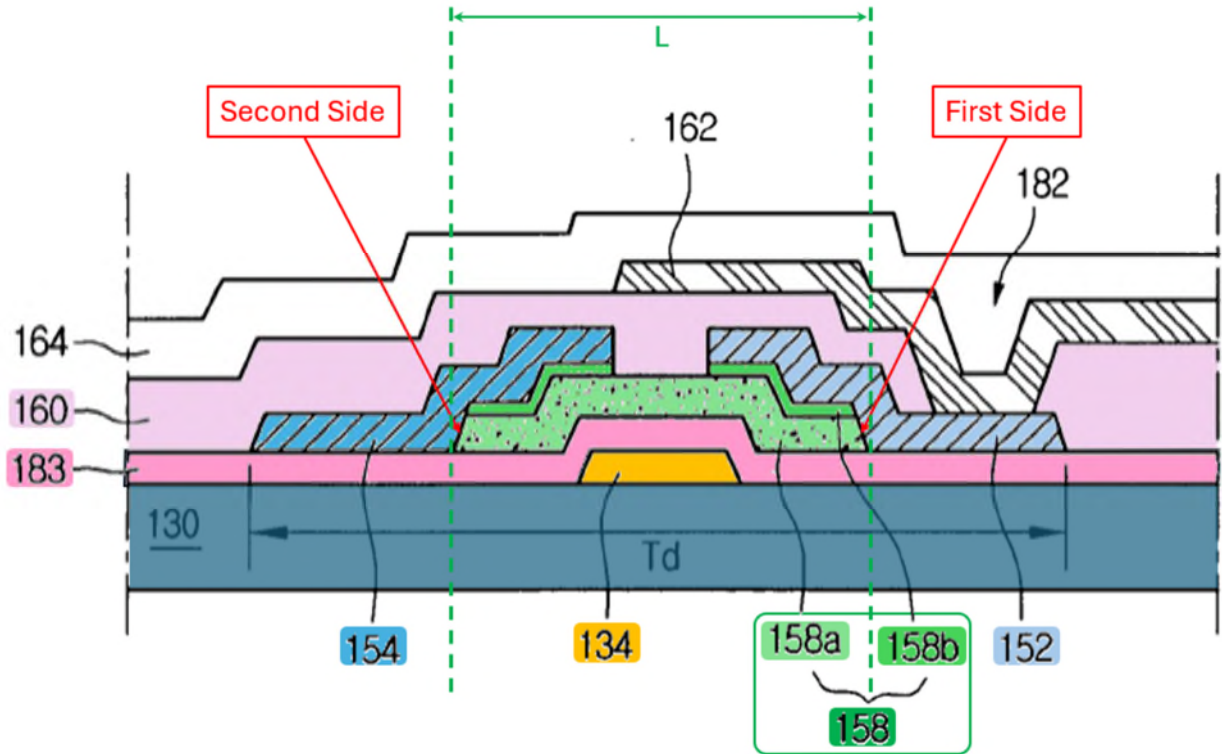
A POSITA would have further recognized that ohmic contact layers 158b are semiconductor layers that are part of the drive transistor whose presence allows

the metal-semiconductor junction (source/drain electrode interface to the source/drain region of the transistor) to have linear  $I-V$  (current-voltage) characteristics. EX1007, 187-189. Therefore, they would be considered part of the claimed channel layer. However, in the Hwang configuration where layers 158a and 158b are vertically stacked, the channel length would be the same regardless of whether the ohmic contact layers are considered part of the claimed channel layer. EX1002, ¶88.

5. **[1d] a source electrode and a drain electrode, located at the two opposite sides of the channel layer, and electrically connected to the first side and the second side of the channel layer, respectively;**

Hwang discloses “a source electrode (152) and a drain electrode (154), located at the two opposite sides of the channel layer (158), and electrically connected to the first side and the second side of the channel layer, respectively.”





EX1004, Fig. 6c (dielectric layer annotated in light pink). Hwang discloses depositing a dielectric material 160 over the entire substrate and thus covers the channel layer and the source and drain electrodes. EX1004, [0081]. EX1002, ¶¶91-92.

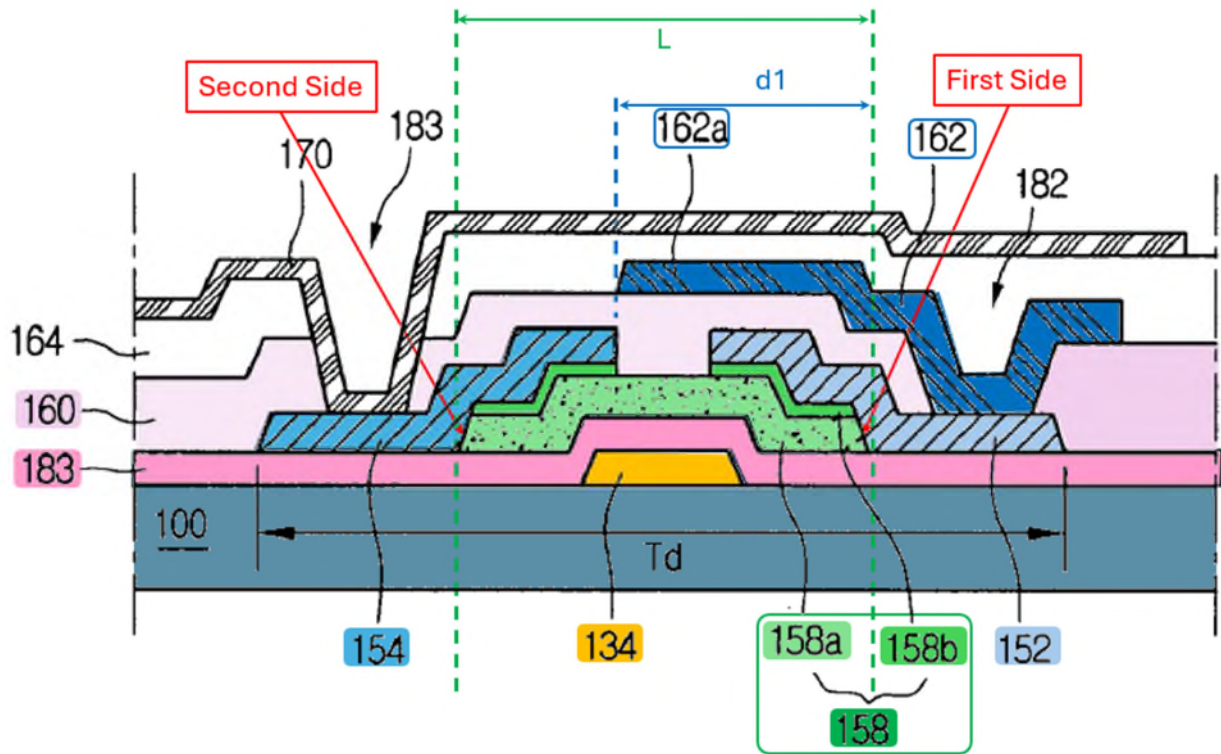
As explained in Figures 2, 3, 6b, 6c and accompanying text, via's are later made through the dielectric material 160 to allow for electrical connections to upper layers. The "cover" limitation does not preclude such openings. Claim 9 requires an OLED and "a lower electrode, disposed on the dielectric layer and electrically connected to the drain electrode." EX1001, claim 9. The specification explains this claimed connection is through a "contact window." EX1001, 4:34-40.

Thus, a POSITA would have understood that “cover” does not preclude such openings. EX1002, ¶93.

7. **[1f] a conductive light-shielding pattern layer, disposed on the dielectric layer, and overlapped to a portion of the source electrode and a portion of the channel layer in a vertical projection, wherein the conductive light-shielding pattern layer does not overlap to the drain in the vertical projection, and the conductive light-shielding pattern layer and the channel layer have an overlapping length  $d_1$ , and  $0.3 \leq d_1/L \leq 0.85$ .**

Hwang discloses “a [conductive light-shielding pattern layer \(162/162a\)](#), disposed on the [dielectric layer \(160\)](#), and overlapped to a portion of the [source electrode \(152\)](#) and a portion of the [channel layer \(158\)](#) in a vertical projection, wherein the conductive light-shielding pattern layer does not overlap to the drain in the vertical projection, and the conductive light-shielding pattern layer and the channel layer have an [overlapping length  \$d\_1\$](#) , and  $0.3 \leq d_1/L \leq 0.85$ .”





EX1004, Fig. 6d (conductive light-shielding pattern layer annotated in dark blue). Hwang discloses patterning a deposited metal layer on dielectric layer 160 to form ground line 162 that also includes an extended portion 162a (“auxiliary electrode) over part of and shields the drive transistor. EX1004, [0083]-[0087]. As shown in the annotated figure above, the length of the overlap between layer 162/162a and the channel layer in a vertical projection (*i.e.*, a direction perpendicular to the plane of the substrate) is annotated as **d1** where layer 162/162a does not overlap the drain electrode 154. EX1004, [0048] and [0050] (disclosing auxiliary electrode 162a does not overlap the drain electrode 154). Further, Hwang expressly discloses aluminum, aluminum alloy, tungsten, copper, molybdenum and



titanium as exemplary metals suitable for layer 162/162a (ground line and auxiliary electrode). EX1004, [0101], claim 13. EX1002, ¶¶94-95.

**a. Material properties of layer 162/162a are electrically conductive and light-shielding (optically opaque)**

As discussed in Claim Construction Section on “a conductive light-shielding layer,” the 471 patent discloses “metal” as the broad class of materials suitable for the conductive light-shielding pattern layer. EX1001, 3:58-61, 4:40-5:9. A POSITA would have readily recognized that the exemplary metals and metal alloys disclosed by Hwang have high electrical conductivity because they are well-known metal materials used for interconnects in semiconductor devices. This recognition is further reinforced by the fact that layer 162 serves as the electrical ground line, and thus would be fabricated with a material that is a good electrical conductor. EX1002, ¶96.

While Hwang does not explicitly teach that layer 162/162a serves the intended purpose of light-shielding, a POSITA would have understood that the layer formed using any one of these exemplary metals would have light-shielding properties for multiple reasons. First, a POSITA would have recognized that these exemplary metals are good reflectors of light. Therefore, most of the light incident on these metal materials are reflected rather than transmitted through the material. *See e.g.*, Paper 39 (Final Written Decision) *Home Depot USA, Inc. v. Lynk Labs, Inc.* IPR2021-01541, at 32 (holding “Aluminum, for example, indisputably reflects

light.”). Light incident on these exemplary metallic surfaces would instead be reflected back, as is well known to those of skill in the art. EX1002, ¶97.

Second, with respect to any light that is not reflected back (which will be a small fraction of the incident light), most of it will be absorbed by these metal materials well before it can travel through the thickness of the material. EX1008, 35.6. A POSITA would have recognized that the absorption rate of light (*i.e.*, an electromagnetic field) as it propagates within a metal material is characterized by its “skin depth,” a parameter indicating the distance where the light intensity has attenuated by about 86.5% due to absorption in the material. EX1008, 35.3-35.7. In other words, after accounting for incident light being reflected at the surface, less than 14% of the light intensity will penetrate past the skin depth, with the light intensity continuing to decrease the further the distance it propagates into the material. EX1002, ¶98.

The skin depth parameter  $\delta$  is given by the formula  $\delta = \sqrt{\frac{2}{\omega\mu\sigma}}$ , where  $\omega$  is the frequency of the electromagnetic wave,  $\mu$  is the magnetic susceptibility of the material, and  $\sigma$  is the electrical conductivity. EX1008, 35.6 (equation 11). This equation shows that the skin depth (or the penetration depth) of an electric field through a material depends inversely on its frequency and on the conductivity of the material, meaning the skin depth will decrease as frequency increases or as conductivity increases. As is well known, metals are highly conductive, and light

oscillates at very high frequencies (light in the visible spectrum is in the Terahertz range, where 1 Terahertz (THz) is  $10^{12}$  oscillations per second). Therefore, both factors contribute to a very small penetration depth for light incident on a metal. Indeed, at optical frequencies, the skin depth of most metals is only approximately 50 nanometers (where one nanometer is one billionth of a meter). EX1008, 35.6. EX1002, ¶99.

The skin depth equation also shows that as the frequency of the electric field decreases, the skin depth parameter increases, meaning the electric field can penetrate deeper into the metal. Thus, to effectively limit the penetration of a lower frequency electromagnetic wave (*e.g.* microwave radiation that oscillates at  $10^6$  –  $10^9$  Hz) using the same material, a thicker layer of that material is required (when compared to a higher frequency electromagnetic wave such as light in the optical spectrum). This is relevant because in Hwang's embodiment of Fig. 6d (shown above), Hwang expressly teaches that auxiliary electrode 162a must shield the channel region of the TFT from the influence of the time-varying electric field caused by electrode 170 when the OLED is driven at different electrical currents to produce different levels of brightness. EX1004, [0014]-[0020], [0050], [0065]-[0068], [0072], [0101]. The frequency bandwidth of these electrical drive signals would be well below optical frequency range, reaching at most the microwave frequency range. As expressly taught by Hwang, auxiliary electrode 162a in Fig.

6d must be sufficiently thick in order to be effective at shielding these relatively low frequency electric fields propagating from electrode 170 when driving the OLED. Because light oscillates at a higher frequency, it will not penetrate Hwang's auxiliary electrode 162a as deeply as the lower frequency electric field induced by the OLED drive signal. Thus, a POSITA would understand that because Hwang's auxiliary electrode 162a is effective at shielding low frequency electric fields from electrode 170 (as expressly disclosed by Hwang), it must necessarily be effective at shielding light also. Accordingly, Hwang's patterned layer 162/162a qualifies as a conductive light-shielding pattern layer, at least because most if not all of the incident light is either reflected back or absorbed by the metal material. EX1002, ¶100.

Third, it is expressly known in the art that metals such as aluminum, aluminum alloy, tungsten, copper, molybdenum and titanium are conductive materials with light-shielding (or light blocking) properties suitable for shielding a semiconductor from light. EX1005, [0006] and [0012] (explaining the use of a gate electrode to shield a semiconductor layer in a TFT from light), [0045] (disclosing the use of metal materials including aluminum, tungsten, copper, molybdenum, titanium and their alloys for the gate electrode); EX1006, [0046] (use of metal wiring layer to shield a TFT from light), [0096] (disclosing the use of aluminum and molybdenum for the light-shielding pattern); EX1012, 7 (disclosing the use of

aluminum and molybdenum for the light-shielding pattern); EX1015, 12:35-44 (disclosing that an aluminum film has high light shielding properties). EX1002, ¶101.

To the extent the Board finds that Hwang does not inherently disclose nor render obvious that auxiliary electrode 162a within layer 162/162a as meeting the light-shielding limitation, it would have been obvious in view of Yamashita to configure Hwang's electrode 162a to be light-shielding, as set forth in Section VIII (Ground 3) below. EX1002, ¶102.

**b. Ratio  $d_1/L$  is between 0.3 and 0.85**

As discussed for [1c] *supra*, Hwang's semiconductor layer 158 has length  $L$  in the channel direction. Layer 158 comprises the source, channel and drain regions of the drive transistor  $T_d$  (in the form of a TFT) for the OLED device. EX1004, [0075]-[0080]. As depicted in Fig. 6a-6d, the source, channel and drain regions of Hwang's transistor  $T_d$  is symmetric with respect to the center of the channel region such that the length<sup>1</sup> of the source and drain regions is the same. Further, Hwang depicts drive transistor  $T_d$  has a channel region (*i.e.*, the part of

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<sup>1</sup> Unless other specified, the term "length" with respect to the source, channel and drain regions as used herein refers to the length in the channel direction.

layer 158 not covered by ohmic contacts 158b, EX1004 [0080]) whose length is no greater than that of the source or the drain regions. EX1002, ¶103.

Thus, a POSITA would review the disclosure in Hwang and at once envisage a commonly-used TFT configuration in which (a) the source and drain regions are equal in length, and (b) where the length of the channel region is no greater than that of the source (or drain) region. At a minimum, Hwang's disclosure would have rendered obvious such a TFT configuration. A POSITA would have recognized this as a common TFT configuration for OLED drive transistors because a shorter channel region length typically allows higher current and faster switching speeds, whereas lithography limits and the necessity for forming highly conductive source/drain contacts typically result in source/drain regions that are similarly sized but larger than the channel region (*i.e.*, condition (b)). Once the source/drain regions are large enough to accommodate electrical connection to highly conductive contacts, TFT drive transistor designs would not further increase those dimensions unnecessarily. This is because a general design goal would be to increase pixel density in an OLED display panel (thus leaving the source and drain regions equally sized, *i.e.*, condition (a)). Thus, a POSITA would have recognized the figures in Hwang to at least render obvious (if not outright depict) a well-known and common TFT drive transistor configuration having relative proportional dimensions as set forth above. EX1002, ¶104.

Based on these two conditions for this common (or at least obvious) TFT configuration, a POSITA can ascertain the range for the length of the drain region as a fraction of the total length  $L$ . For fixed  $L$ , the drain region length reaches a value of approximately  $0.33L$  where the source, channel and drain regions are of equal lengths. A POSITA would have recognized that transistor performance generally improves (*e.g.*, higher speed and greater power efficiency) when the length of the channel region is reduced. EX1013, 33-37. This performance improvement is the basis for the drive towards miniaturization of semiconductor devices, manifesting itself as the well-known Moore's Law. Accordingly, a POSITA would have recognized that common transistor designs may have a channel region length that is less than the length of the source/drain regions due to the advantages of a decreased channel region length. EX1013, 33-37. Since the drain region length is equal to  $0.33L$  (when the source, drain and channel regions are equal lengths), decreasing the length of the channel region relative to the source/drain region would lead to a corresponding increase in the source/drain region length such that it is greater than  $0.33L$ . Therefore, a POSITA would have recognized that for many common transistor configurations,  $0.33L$  would be a typical lower bound for the drain channel length. Of course, a POSITA would also have recognized that the channel region length cannot be reduced too much because of fabrication tolerances and also because of the well-known short channel

effect. EX1007, 298-299, 325-327. However, even if we consider an extreme hypothetical design where the channel region length is negligibly small relative to the equally-sized source and drain regions (such that each of these regions make up 50% of the semiconductor layer 158), the drain region length would still reach a maximum value of no greater than  $0.5L$ . Thus, the relative size of the drain region is bounded between  $0.33L$  and  $0.5L$ . Since the source region is the same size as the drain region, its length is likewise bounded between  $0.33L$  and  $0.5L$ . The length of the channel region would make up the difference (*i.e.*,  $L$  - length of source - length of drain), thus ranging between approximately  $0L$  (in the extreme hypothetical case) to  $0.33L$ . EX1002, ¶105.

Hwang discloses the conductive light-shielding pattern layer 162/162a to overlap both the source and channel regions, but not the drain region. Therefore, the overlapping length  $d_1$  is  $(L - \text{length of drain})$  which is between  $0.5L$  and  $0.67L$ . Accordingly, a POSITA would have recognized that any TFT drive transistor  $T_d$  so configured would result in a  $d_1/L$  ratio to fall between  $0.5$  to  $0.67$ , the entirety of which falls within the claimed range of  $0.3$  to  $0.85$ . EX1002, ¶106.

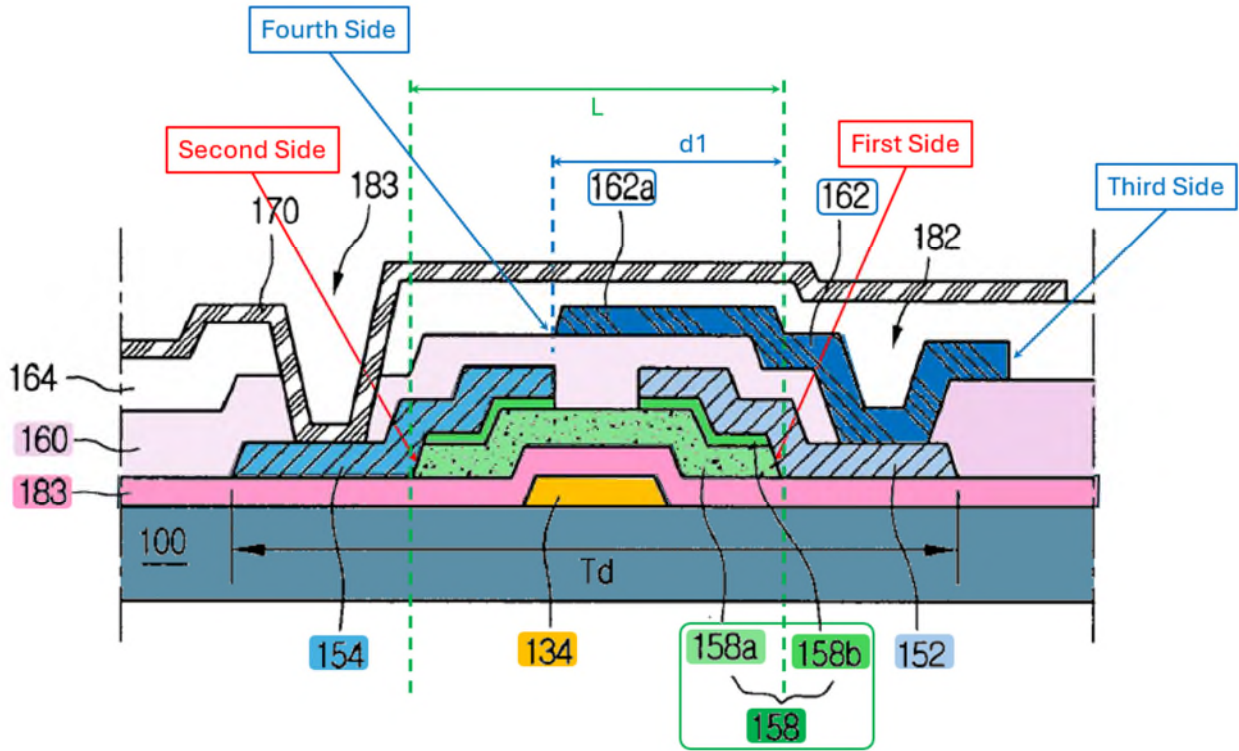
Alternatively, it would have been obvious to a POSITA to take the figures in Hwang at face value and glean therefrom relative dimensions for the length of the source, drain and channel regions of driving transistor  $T_d$  to be approximately  $0.38L$ ,  $0.38L$  and  $0.24L$  respectively. A POSITA applying the teachings of Hwang



regarding layer 162/162a to not overlap with the drain region of driving transistor Td would arrive at a conductive light-shielding pattern layer having a  $d1/L$  value of 0.62L, which falls well within the claimed range of 0.3 to 0.85. EX1002, ¶¶107-109.

- D. Claim 4. The semiconductor structure as claimed in claim 1, wherein the conductive light-shielding pattern layer has a third side and a fourth side along the channel direction, the fourth side is overlapped to the channel layer in the vertical projection, wherein the overlapping length  $d1$  is equal to a distance between the fourth side and the first side of the channel layer along the channel direction.**

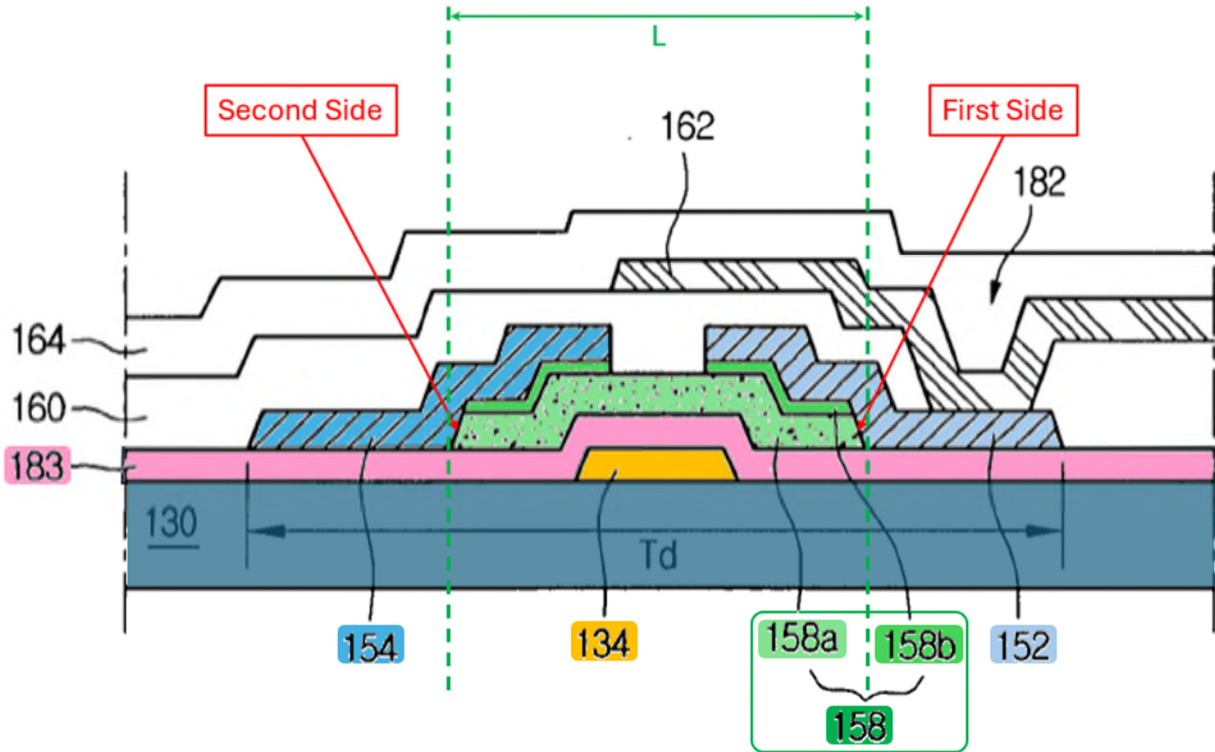
Hwang discloses “the [conductive light-shielding pattern layer \(162/162a\)](#) has a [third side](#) and a [fourth side](#) along the channel direction, the fourth side is overlapped to the channel layer in the vertical projection, wherein the [overlapping length  \$d1\$](#)  is equal to a distance between the fourth side and the first side of the channel layer along the channel direction.”



EX1004, Fig. 6d (annotations added identifying length  $d1$  between fourth side of layer 162/162a and the first side of channel layer 158). EX1002, ¶¶110-111.

**E. Claim 6. The semiconductor structure as claimed in claim 1, wherein the source electrode and the drain electrode respectively cover a portion of the channel layer.**

Hwang discloses “the source electrode (152) and the drain electrode (154) respectively cover a portion of the channel layer (158).”



EX1004, Fig. 6c annotated showing the source and drain electrodes cover a portion of the channel layer. EX1002, ¶¶112-113.

**F. Claim 9**

- 1. [9pre] An organic electroluminescence device, disposed on a substrate, and comprising.**

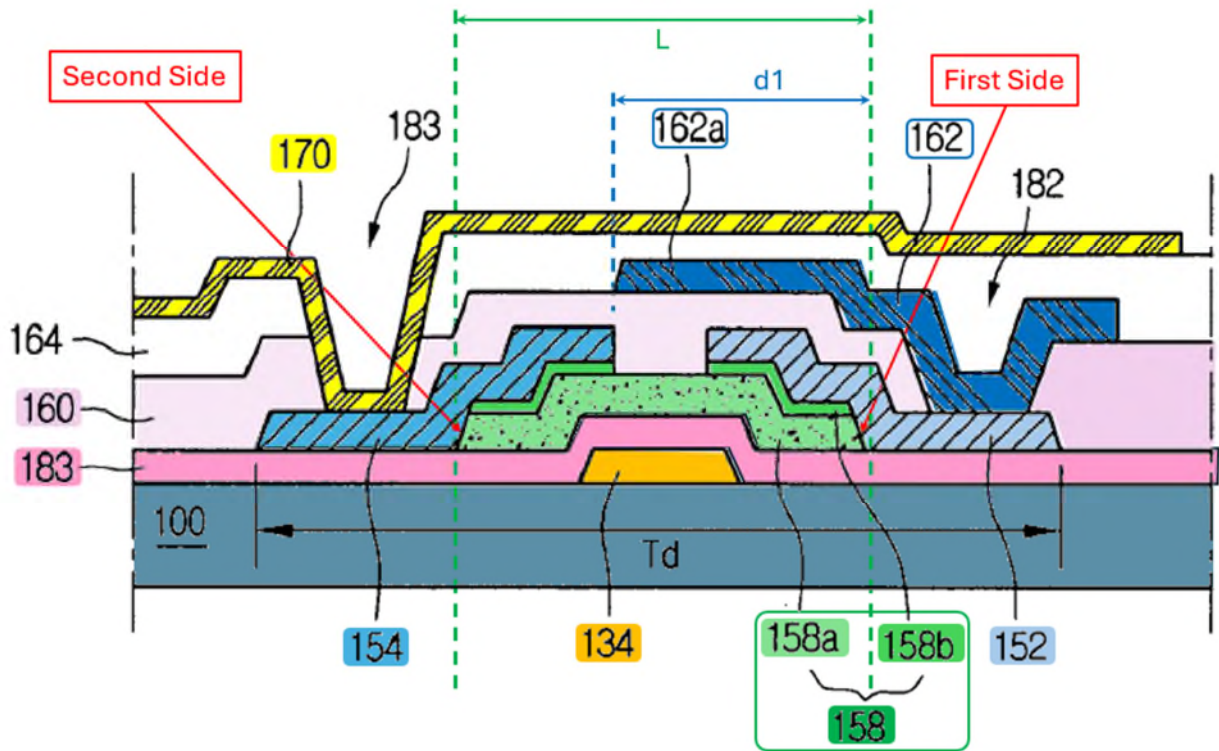
*See* [1pre], [9a]-[9i] (including drive transistor and organic light emitting layer of the OLED that are part of the organic electroluminescence device).

- 2. [9a]-[9f];**

*See* [1a]-[1f].

3. [9g] a lower electrode, disposed on the dielectric layer and electrically connected to the drain electrode;

Hwang discloses “a lower electrode (170), disposed on the dielectric layer (160) and electrically connected to the drain electrode (154).”



EX1004, Fig. 6d (lower electrode 170 annotated in yellow shading, disposed on dielectric layer 160 and in contact with drain electrode 154). A POSITA would have recognized that electrode 170 is disposed on dielectric layer 160 because of the sloped openings formed within layer 160 to allow electrode 170 to make direct contact with the drain electrode 154. Thus, within at least that sloped opening, electrode 170 is directly disposed on the sidewalls of layer 160. Further, a POSITA would have recognized that electrode 170 is indirectly disposed on layer 160 in

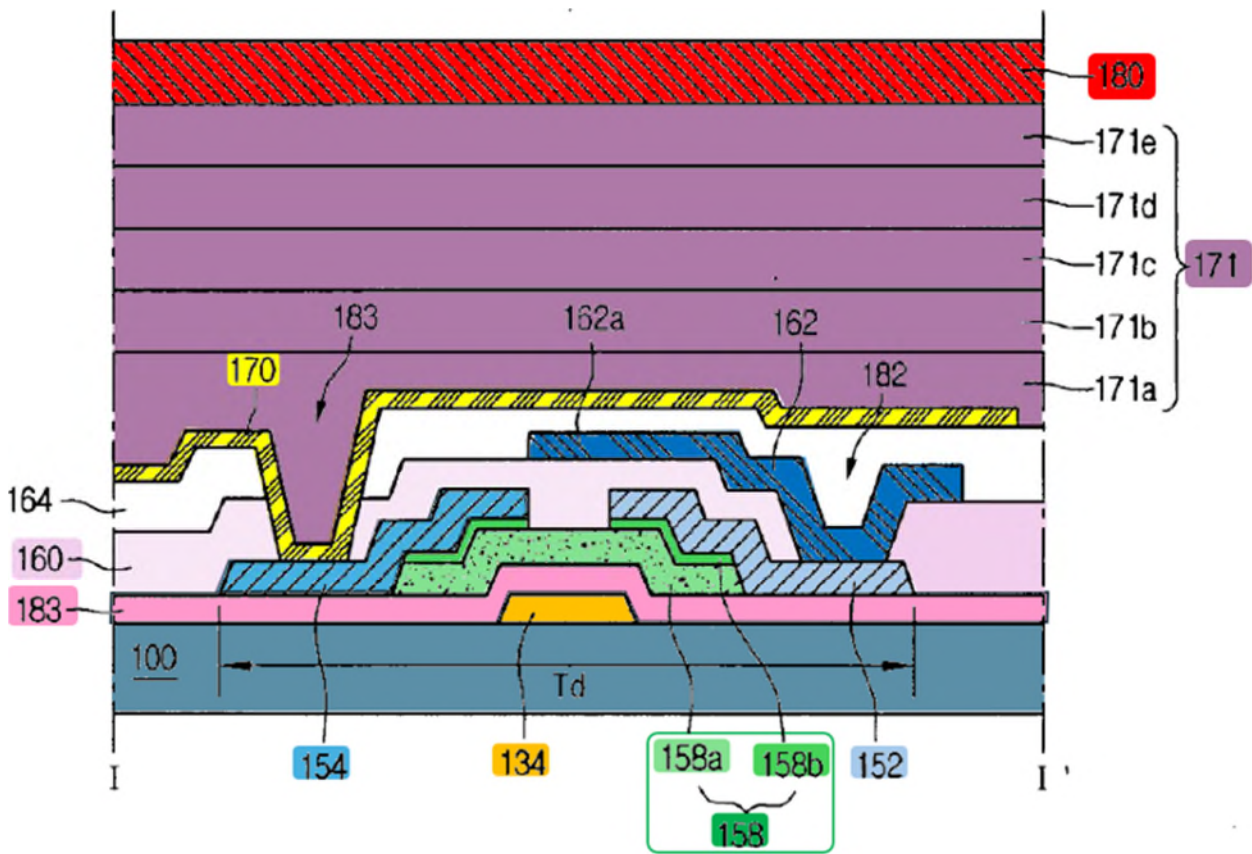




(showing 171 disposed on 170), [0053]-[0054] (“An organic light emitting layer 171 ... are formed on the first electrode 170.”), [0093]-[0095] (light emitting layer 171 may be a single layer or multiple layers). EX1002, ¶¶118-119.

**5. [9i] an upper electrode, disposed on the organic light emitting layer.**

Hwang discloses “an upper electrode (180), disposed on the organic light emitting layer (171).”



EX1004, Fig. 3 (annotations added). The first embodiment in Hwang (Figures 1-6 and accompanying text) discloses that the embodiment depicted therein includes an organic light emitting layer (171) formed on the first electrode

170. EX1004, Fig. 3 (showing 180 disposed on 171), [0053]-[0057] (“An organic light emitting layer 171 and a second electrode 180 are formed on the first electrode 170.”), [0061], [0093]-[0094] (“The second electrode serves as an anode”), [0095] (light emitting layer may be a single layer or multiple layers).  
EX1002, ¶¶120-121.

**G. Claim 12.**

*See* claim 9, claim 4.

**H. Claim 14.**

*See* claim 9, claim 6.

**I. 17. The semiconductor structure as claimed in claim 1, wherein the conductive light-shielding pattern layer and the drain electrode are spaced by a distance along the channel direction in the vertical projection.**

Hwang discloses, or at least renders obvious, “the semiconductor structure as claimed in claim 1 (*see* claim 1), wherein the [conductive light-shielding pattern layer \(162/162a\)](#), and the [drain electrode \(154\)](#) are spaced by a distance along the channel direction in the vertical projection.” EX1002, ¶124.

Hwang teaches layer 162/162a should cover the channel region and not overlap the drain electrode 154. EX1004, [0048]. As illustrated in Figure 6d, Hwang teaches that in the vertical projection, there may be very little space between the end of the drain electrode 154 and electrode 162a. EX1004, Fig. 6d. To the extent Figure 6d does not expressly disclose electrode 162a and drain

electrode 154 are “spaced by a distance in the vertical projection,” Hwang also teaches that, while electrode 162a covers the channel region to block the influence of electrode 170, it could be shortened, depending on need. EX1004, [0050] (“auxiliary electrode 162a. . . does not overlap the second drain electrode 154. The auxiliary electrode 162a may be . . . shorter . . . upon need.”). One exemplary need disclosed by Hwang is to prevent short circuit between the auxiliary electrode 162a and the drain electrode 154. EX1004, [0050]. Thus, Hwang teaches that electrode 162a (which still should cover the channel region to block the influence of electrode 170) can be shortened (*i.e.*, spaced apart in the vertical projection) by a small amount to account for fabrication variances in order to mitigate a potential short circuit to the drain electrode. Because this claim does not require a particular minimum amount of distance for the “spaced apart” limitation, Hwang’s wholistic teaching that electrode 162a covers the channel, does not overlap the second drain electrode and can, in fact, be even shorter expressly discloses this claim to a POSITA. EX1002, ¶125.

Additionally or alternatively, claim 17 is obvious in view of Hwang. A POSITA would have understood that Hwang’s teaching in paragraph [0050] related to shortening electrode 162a would not expose the entire channel region entirely, but only to shorten electrode 162a to the extent needed. This is because the disclosed function of the auxiliary electrode 162a is to shield the channel



region from the electric potential at the cathode 170. Indeed, this shielding of the channel region from the cathode voltage specifically solves the problem that Hwang's invention sought to overcome. EX1004, [0016]. Specifically, shielding the channel region overcomes the problems of brightness deterioration and non-uniformity. EX1004, [0072]; *see also id.*, [0069]-[0074] and Fig. 5. Therefore, a POSITA would have understood that shielding the channel region remains important, even though there may be other design tradeoffs that need to be considered. EX1002, ¶126

For example, as disclosed in Hwang, increasing the spacing would help prevent an unintentional short circuit between auxiliary electrode 162a (which is electrically connected to and thus on the same node as the source electrode) and the drain electrode 154. EX1004, [0050], [0066]. Additionally or alternatively, a POSITA would have recognized that unintended parasitic capacitance between the source and drain has an adverse impact on the transistor performance. EX1007, 323. Thus, a POSITA would have been motivated to mitigate unintended capacitive coupling to the drain electrode 154 by increasing the spacing (in the vertical projection) between electrode 162a and drain electrode 154 for a given dielectric material 160 to increase the distance therebetween, thereby reducing the resulting capacitance. EX1014, 153-154. EX1002, ¶127.

A POSITA would have recognized that even though electrode 170 is electrically connected to drain electrode 154, capacitive coupling between electrode 162a and electrode 170 can be mitigated by increasing the properties (*e.g.*, thickness and/or dielectric constant) of dielectric layer 164. However, this does not fully resolve the potential capacitive coupling to the drain electrode, thus potentially requiring additional spacing between electrode 162a and drain electrode 154 (as expressly taught by Hwang). Thus, the extent of the overlap of electrode 162a with the channel region requires a tradeoff between mitigating unintentional short circuits and/or the capacitive coupling to the drain and shielding the effects of the cathode on the channel region. Any decrease in the overlap length would necessarily cause electrode 162a and drain electrode 154 to be spaced by a distance along the channel direction in the vertical projection. EX1002, ¶128.

As for quantifying the decrease in electrode 162a, a POSITA would have recognized from the teachings of Hwang that the primary emphasis remains to provide as much shielding to the channel region as possible in order to reap the benefits of the Hwang invention. EX1004, [0069]-[0074]; Fig. 5. Therefore, this would have suggested to a POSITA that at least half of the channel region should remain shielded (if not more) in balancing these other considerations while still preserving the main teachings in Hwang for improving performance by shielding the channel region. This results in a minimum  $d1/L$  ratio of 0.5 with no change to

the maximum  $d1/L$  ratio (0.67), which remains within the range claimed in [1f].

EX1002, ¶129.

- J. 18. The organic electroluminescence device as claimed in claim 9, wherein the conductive light-shielding pattern layer and the drain electrode are spaced by a distance along the channel direction in the vertical projection.**

*See* claim 9, claim 17.

## **VII. GROUND 2: HWANG AND GODO**

### **A. Relationship to Ground 1**

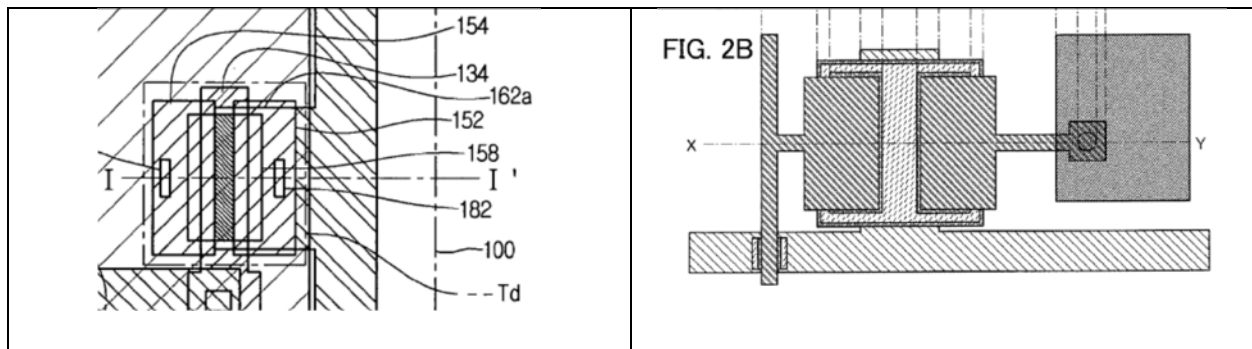
Hwang renders obvious the claims as set forth above for Ground 1 which is incorporated herein by reference.

In the alternative, to the extent the claimed relative dimensions of the source, channel and drain regions of a TFT are not taught or rendered obvious to a POSITA by Hwang alone such that the resulting device would meet the claimed  $d1/L$  ratio (as set forth in [1f] and [9f]), those dimensions would have been rendered obvious over the combination of Hwang and Godo. As discussed below, Godo discloses specific dimensions for bottom gate TFTs. EX1005, [0199], [0201], Figs. 1A, 1B, 2A, 2B, 4A, 4B, 20A and 20B. EX1002, ¶¶131-132.

### **B. The Combination**

1. Hwang broadly discloses an arrangement of semiconductor materials to form a TFT, and metallic materials for shielding the channel region in the transistor in an organic luminescent device. The combination of Hwang and Godo

modifies Hwang's general teachings for a broad genus of TFTs with Godo's disclosure of more particular species of TFTs (with specific dimensions for the source, channel and drain regions for the transistor) according to known methods to yield predictable results. Compare, e.g., EX1004, Fig. 2 (top-down view of drive transistor Td) and EX1005, Fig. 2B (*see also* Figs. 4B and 20B).



As discussed in Ground 1, [1f], suitable dimensions for such transistors would have been well known in the art, and a POSITA would have immediately recognized Hwang's Figures 6a-6d to at least disclose a broad class of TFTs with at least known ranges of relative proportions for the dimensions of the source, channel and drain regions of the transistor. Nevertheless, to the extent a POSITA, upon reviewing Hwang's disclosure, would have remained unaware of suitable dimensions for the drive transistor, the POSITA would have been motivated to investigate known suitable dimensions in the art for transistors suitable for driving an LED device and been led to Godo's disclosures of appropriate dimensions. EX1005, [0150], [0161], [0163] (disclosing TFT 420 is a drive transistor), [0165] (disclosing TFT 420 drives LED element 430), [0199], [0201]; Figs. 1A-2B, 4A,

4B, 18A, 18B, 20A (with one set of dimensions) and 20B (another set of dimensions). EX1002, ¶133.

A POSITA would have recognized that Godo's Fig. 4B TFT design shares the most similarities with Hwang's Fig. 6 TFT design: a single amorphous Si channel layer and a bottom gate electrode whose length in the channel direction is less than the length of the amorphous Si layer. Therefore, it would have been obvious to a POSITA to use Godo's Fig. 4B dimensions, at least as a starting point, and potentially consider using Godo's other disclosed dimensions as well. As will be demonstrated below, the resulting  $d_1/L$  ratios for each of Godo's disclosed TFTs meet the claimed range for limitations [1f] and [9f]. Therefore, regardless of which set of TFT dimensions a POSITA uses from Godo to modify Hwang, limitations [1f] and [9f] are still rendered obvious. EX1002, ¶134.

A POSITA would have had a reasonable expectation of success in making the proposed combination because techniques such as photolithography for defining patterns for forming transistor elements with the disclosed dimensions were well known in the art. Patterning feature sizes that are in the micron ( $\mu\text{m}$ ) resolution were well within the ordinary state of the art. Further, the relevant transistors disclosed in both Hwang and Godo are both bottom gate TFTs. EX1004, Figs. 6a-6d; EX1005, Figs. 1A-2B, 4A-B. Thus, the only "modification" of Hwang is to supplement Hwang with the specific geometric dimensions taught

in Godo to form Hwang's lithography masks, then perform the same standard and routine TFT fabrication steps to thereby form a transistor with the dimensions as disclosed in Godo. The proposed combination would not have required undue experimentation and would have yielded the predictable result, namely, a drive transistor with the dimensions as disclosed in Godo. Once the drive TFT is formed, Hwang's layer 162/162a with the shielding auxiliary electrode can be formed thereafter as taught by Hwang. EX1002, ¶135.

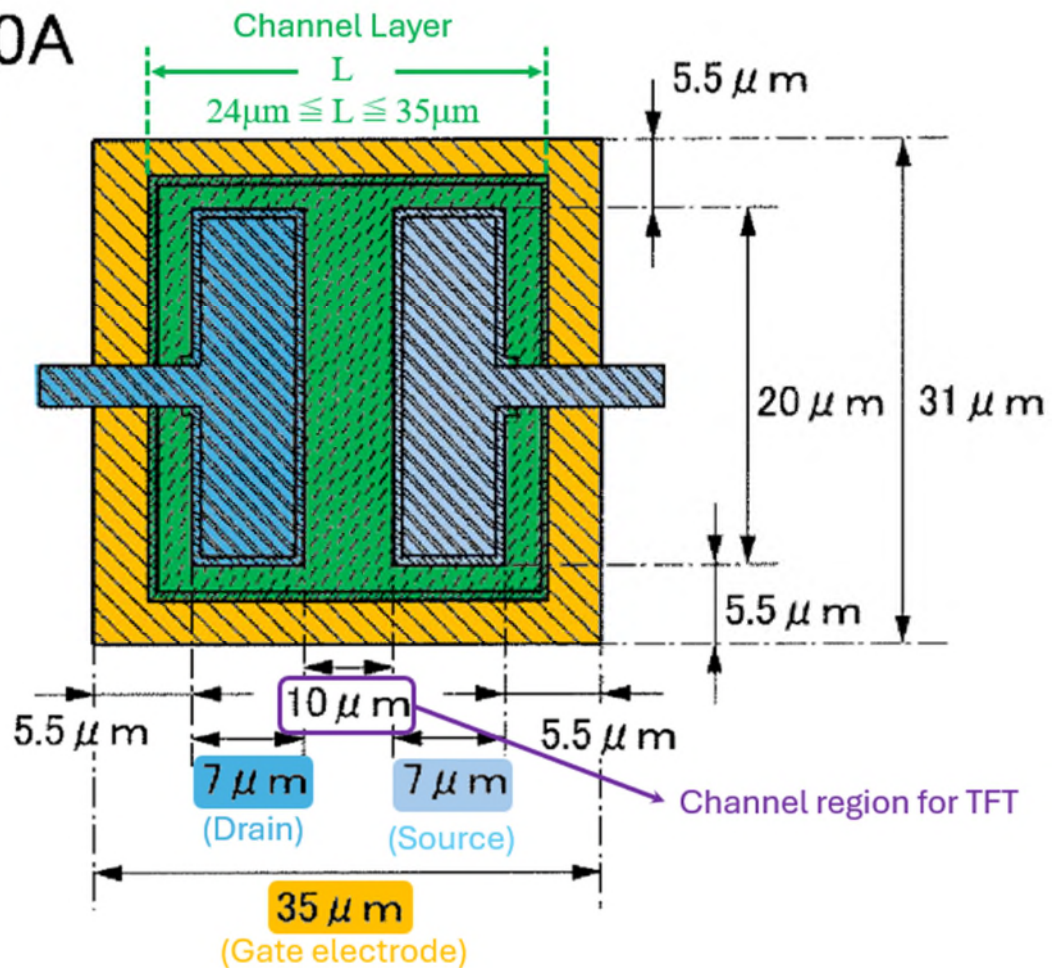
**C. “... an overlapping length  $d_1$ , and  $0.3 \leq d_1/L \leq 0.85$ ” ([1f], [9f])**

Godo discloses the dimensions for the source, channel, and drain regions for TFTs suitable for driving an LED device. EX1005, Figs. 20A, 20B; *see also id.*, [0150], [0161], [0199], [0201] (explaining the dimensions shown for Figs, 20A and 20B apply to the transistors of Figs. 1A-2B, 4A and 4B); Figs. 1A-2B, 4A, 4B, 18A, 18B. To the extent a POSITA, having reviewed Hwang's disclosure, required additional express guidance on suitable TFT dimensions, the POSITA would have been motivated to seek out those teachings in the art and it would have been obvious to use the TFT dimensions disclosed in Godo as explained above. As will be shown below, forming a drive transistor Td (using either Godo's Fig. 20A or Fig. 20B dimensions), and thereafter forming layer 162/162a that shields the source and channel regions of drive transistor Td would result in  $0.3 \leq d_1/L \leq 0.85$  as required by this limitation. EX1002, ¶136.

1. **Godó's Fig. 20A dimensions render obvious claimed  $d1/L$  ratio**

The TFT shown in Godó's Fig. 20A has a channel direction that runs left/right, and the length of source and drain regions along the channel direction are  $7\mu\text{m}$ . The length of the channel region is  $10\mu\text{m}$ .

FIG. 20A



EX1005, Fig. 20A (annotations added). The length of the channel layer ("L" as claimed in [1c] and [9c]) is not expressly disclosed, but a POSITA would have understood that the disclosed dimensions necessarily bound the range of L. In

particular, L must be less than 35 $\mu\text{m}$  (the length of the gate electrode), but also greater than the sum of the source<sup>2</sup>, channel and drain regions (7 $\mu\text{m}$  + 10 $\mu\text{m}$  + 7 $\mu\text{m}$  = 24 $\mu\text{m}$ ), *i.e.*, 24 $\mu\text{m}$   $\leq$  L  $\leq$  35 $\mu\text{m}$ . EX1002, ¶137.

As for the d1 dimension, as discussed in [1f] for Ground 1, Hwang's layer 162/162a has overlap length d1 that shields at least the source and channel regions. Thus, applying Godo's dimensions, the minimum value for d1 is 17 $\mu\text{m}$  (the sum of source region and channel region lengths). Further, based on the teachings of Hwang that the drain electrode should not be shielded by layer 162/162a), the maximum value for d1 would be the entire channel layer except for the drain, *i.e.*, d1  $\leq$  L - 7 $\mu\text{m}$ . EX1002, ¶138.

	d1 ( $\mu\text{m}$ )	L ( $\mu\text{m}$ )
Minimum	17	24
Maximum	L-7	35

Based on these allowable ranges for d1 and L, the allowable range of d1/L can be determined. The minimum value for the fraction d1/L is achieved when the

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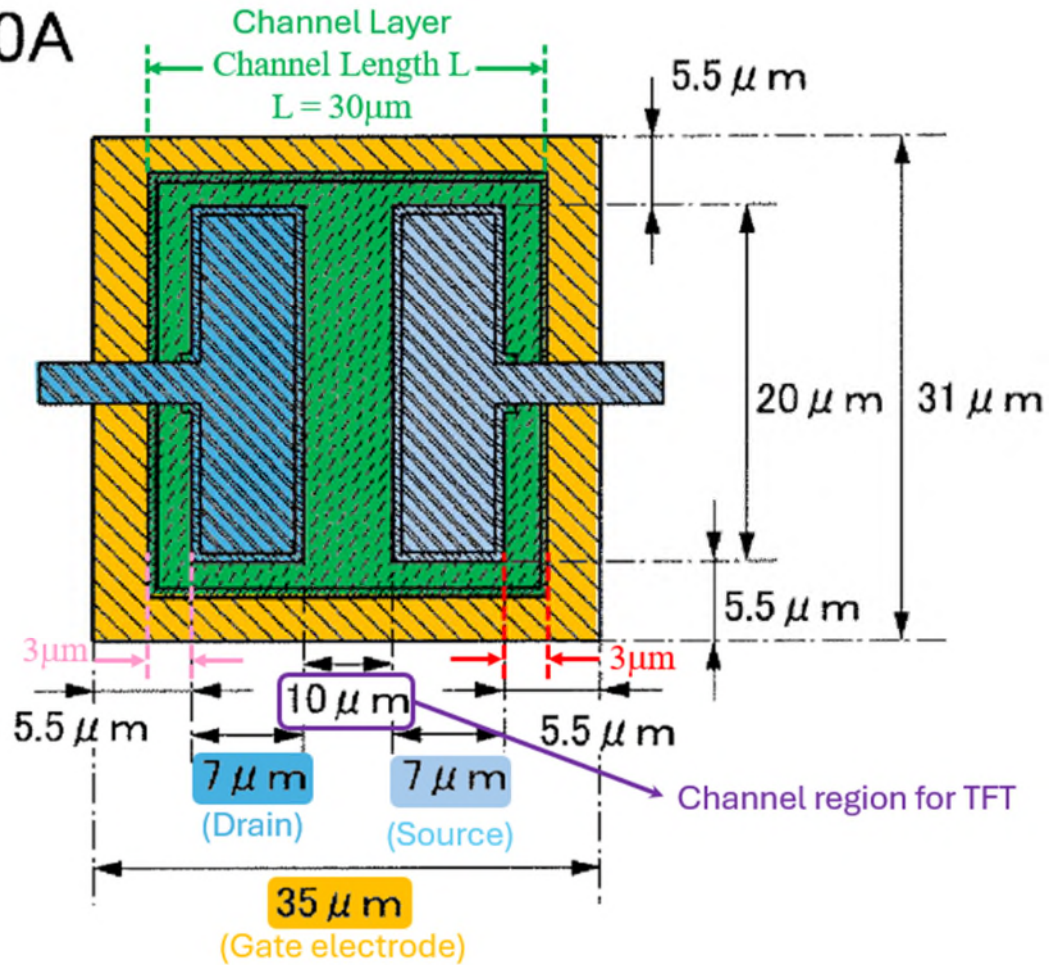
<sup>2</sup> This calculation includes only the lengths for the source region, channel region and drain region as disclosed in Godo because it seeks the lower bound for L. In other words, for a transistor to be consistent with the Godo disclosure, the length L must be large enough to accommodate the three expressly disclosed lengths, which is 24 $\mu\text{m}$ . EX1002, ¶137 n.5.



numerator  $d_1$  is minimized and the denominator  $L$  is maximized, *i.e.*,  $d_{1_{\min}}/L_{\max}$  is  $17\mu\text{m}/35\mu\text{m} = 0.48$ . To maximize  $d_1/L$ , the maximum value for  $d_1$  is  $L-7\mu\text{m}$  as shown above. Substituting, the ratio  $d_{1_{\max}}/L = (L-7\mu\text{m})/L = 1-7/L$ . Thus,  $d_1/L$  is maximized when  $7/L$  is minimized, *i.e.*, when  $L$  is maximized where  $L = 35\mu\text{m}$ . Thus, the maximum  $d_1/L$  ratio is  $1-7/35 = 1-0.2 = 0.8$ . Accordingly, using Godo's dimensions as disclosed in Fig. 20A, the resulting  $d_1/L$  must be between  $0.48 \leq d_1/L \leq 0.8$ , wholly within the range as claimed in [1f] and [9f]. Stated differently, applying Hwang's teachings regarding shielding layer 162/162a on any transistor that is sized consistent with the express dimensions disclosed in Godo's Fig. 20A will necessarily result in  $d_1/L$  between  $0.48 \leq d_1/L \leq 0.8$ . EX1002, ¶¶138-139.

An illustrative example of a TFT layout consistent with the dimensions of Godo's Fig. 20A is provided below, where the exemplary layout has mirror symmetry about the center of the channel region, and where  $L$  is  $30\mu\text{m}$  (which is near the middle of the allowed range).

FIG. 20A



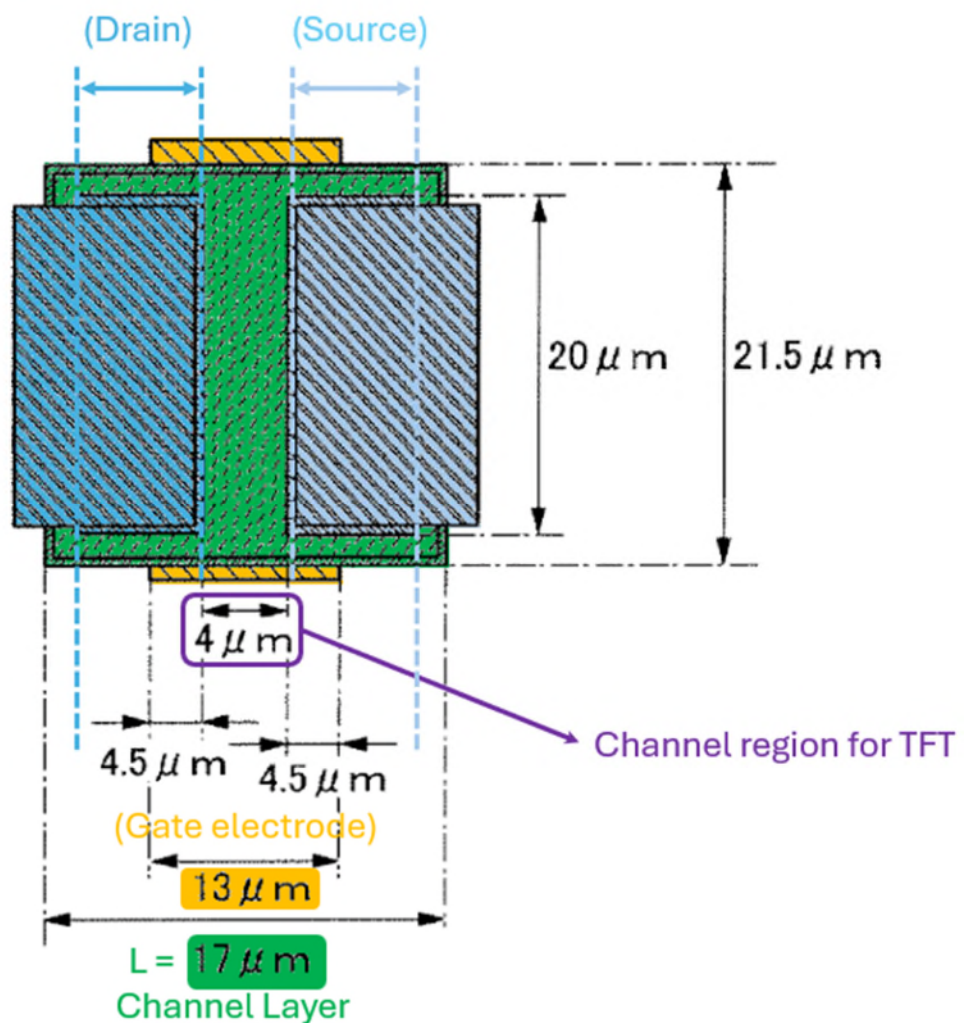
EX1005, Fig. 20A (annotations added). Mirror symmetry means the length between the right-edge of the source region to the right-edge of the (green) channel layer is  $3 \mu\text{m}$  (*i.e.*, the length between the two dotted red lines), which is also the length between the left-edge of the drain region to the left-edge of the channel layer (*i.e.*, the length between the two dotted pink lines). Hwang discloses that shielding layer 162/162a would extend from the right-edge of channel layer, covering the source region and the channel region and stopping at the drain region. This means  $d1 = 3 \mu\text{m} + 7 \mu\text{m} + 10 \mu\text{m} = 20 \mu\text{m}$ , while  $L = 30 \mu\text{m}$ . This leads to an

illustrative value of  $d1/L$  of 0.67, which falls within the claimed range. Of course, this is but one illustrative example, whereas the more general analysis shows that any TFT with dimensions consistent with Godo's Fig 20A necessarily result in a  $d1/L$  within the claimed range. EX1002, ¶140.

**2. Godo's Fig. 20B dimensions render obvious claimed  $d1/L$  ratio**

The TFT shown in Godo's Fig. 20B has a channel direction that runs left-right, and the length of the channel layer is  $17\mu\text{m}$ .

**FIG. 20B**



EX1005, Fig. 20B (annotations added). The channel region has length  $4\mu\text{m}$ , but the exact lengths of the source/drain regions are not expressly disclosed, only that they are at least  $4.5\mu\text{m}$ . The maximum source/drain length can be determined because the sum of the lengths of the source, channel and drain regions cannot exceed the channel layer length of  $17\mu\text{m}$ . Thus, the maximum length for the source region is  $8.5\mu\text{m}$  (taking the length of drain at the minimum  $4.5\mu\text{m}$ ), and the maximum length for the drain is  $8.5\mu\text{m}$  (minimizing the source). EX1002, ¶141.

As for the  $d1$  dimension, as discussed in [1f] for Ground 1, Hwang's layer 162/162a has overlap length  $d1$  that shields at least the source and channel regions. Thus, applying Godo's Fig. 20B dimensions, the minimum value for  $d1$  is  $8.5\mu\text{m}$  (the sum of channel region length and the minimum source region length). Further, based on the teachings of Hwang that the drain electrode should not be shielded by layer 162/162a, the maximum value for  $d1$  would be the entire channel layer except for the drain length (which should be minimized), *i.e.*,  $d1 \leq 17 - 4.5\mu\text{m}$ . EX1002, ¶142.

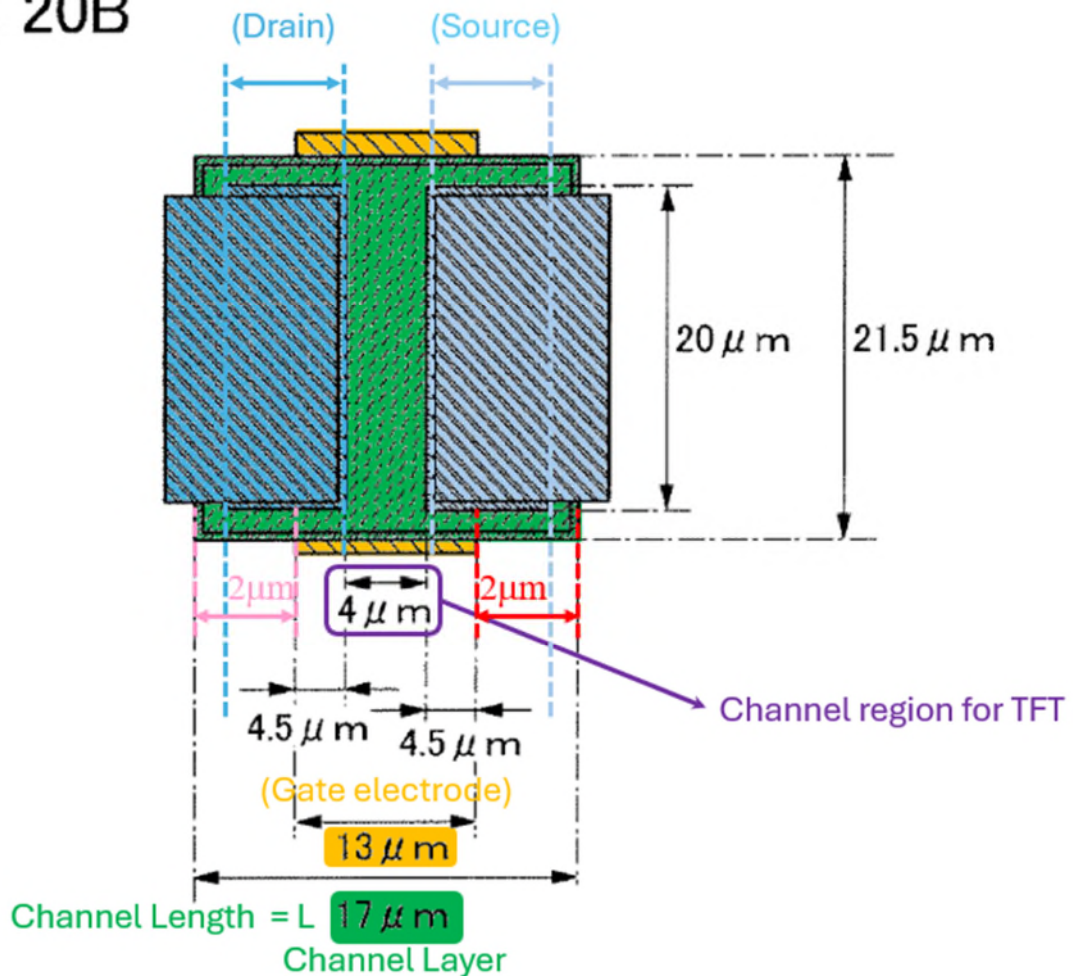
	$d1$ ( $\mu\text{m}$ )	$L$ ( $\mu\text{m}$ )
Minimum	8.5	17
Maximum	12.5	17

Based on these allowable  $d1$  values and the disclosed  $L$  dimension, the ratio  $d1/L$  must be between  $8.5/17$  and  $12.5/17$ , or  $0.5 \leq d1/L \leq 0.735$ , wholly within the range as claimed in [1f] and [9f]. Stated differently, applying Hwang's teachings

regarding shielding layer 162/162a on any transistor that is sized consistent with the express dimensions disclosed in Godo's Fig. 20B will necessarily result in  $d1/L$  between  $0.5 \leq d1/L \leq 0.735$ . EX1002, ¶¶142-143.

An illustrative example of a TFT layout consistent with the dimensions of Godo's Fig. 20B is provided below, where the exemplary layout has mirror symmetry about the center of the channel region.

FIG. 20B



EX1005, Fig. 20A (annotations added). Mirror symmetry means the length between the right-edge of the gate electrode to the right-edge of the (green)

channel layer is  $2\mu\text{m}$  (*i.e.*, the length between the two dotted red lines), which is also the length between the left-edge of the gate electrode to the left-edge of the channel layer (*i.e.*, the length between the two dotted pink lines). Hwang discloses that shielding layer 162/162a would extend from the right-edge of channel layer, covering the source region and the channel region and stop at the drain region. This means  $d1 = 2\mu\text{m} + 4.5\mu\text{m} + 4\mu\text{m} = 10.5\mu\text{m}$ , while  $L = 17\mu\text{m}$ . This leads to an illustrative value of  $d1/L$  of 0.62, which falls within the claimed range. Of course, this is but one illustrative example, whereas the more general analysis shows that any TFT with dimensions consistent with Godo's Fig 20B necessarily result in a  $d1/L$  within the claimed range. EX1002, ¶144

Accordingly, Hwang in combination with Godo discloses the  $d1/L$  dimensional ratio limitation recited in [1f] and [9f], and thus renders obvious claims 1 and 9. EX1002, ¶145

Dependent claims 4, 6, 12 and 14 are not impacted by the  $d1/L$  ratio and therefore the limitations recited therein are disclosed by Hwang or rendered obvious for the same reasons as set forth in Ground 1. EX1002, ¶146.

**D. Claims 17 and 18: "... wherein the conductive light-shielding pattern layer and the drain electrode are spaced by a distance along the channel direction in the vertical projection."**

Regarding dependent claims 17 and 18, the antecedent basis for the conductive light-shielding pattern layer recited therein comes from limitation [1f]

or [9f]. Therefore, layer 162/162a meets the limitations recited in those dependent claims for at least the same reasons set forth above. Further, regarding the “spaced by a distance...” limitation, Hwang teaches that depending on need, some designs may shorten electrode 162a thus leading to the conductive light-shielding pattern layer and the drain electrode to be spaced by a distance along the channel direction in the vertical projection. *See* discussion in Ground 1, Claim 17 regarding EX1004, [0050], incorporated by reference herein. As discussed therein, a POSITA would have applied Hwang’s teachings about shortening electrode 162a in Hwang’s paragraph [0050] (based on balancing different needs of a particular design) such that more than half of the channel region remains shielded. EX1002, ¶147.

Shortening electrode 162a would decrease the  $d_1$  parameter and thereby reduce the  $d_1/L$  ratio. Therefore, the upper bound for  $d_1/L$  will still remain within the claimed range for [1f] and [9f]. To investigate the impact of the modification on the lower bound of  $d_1/L$ , the relative proportions of the transistor dimensions as disclosed in Godo’s Fig. 20A can be used, and then auxiliary electrode 162a shortened as set forth above (*i.e.*, shielding half of the channel region). Thus, the minimum overlap length  $d_1$  is equal to the sum of the length of the source region ( $7\mu\text{m}$ ) and half the length of the channel region ( $5\mu\text{m}$ ), or  $12\mu\text{m}$ . The allowable range for length  $L$  is unchanged (with a range between  $24\mu\text{m}$  and  $35\mu\text{m}$ ), leading

to  $0.34 \leq d1/L \leq 0.5$ , which remains within the claimed range of [1f] and [9f].

EX1002, ¶148.

Using the relative proportions of the transistor dimensions as disclosed in Godo's Fig. 20B and shortening electrode 162a as set forth above, the overlap length  $d1$  is decreased by half of the length of the channel region, *i.e.*,  $2\mu\text{m}$ .

	Revised $d1$ ( $\mu\text{m}$ )	$L$ ( $\mu\text{m}$ )
Minimum	$8.5 - 2 = 6.5$	17
Maximum	$12.5 - 2 = 10.5$	17

This leads to a ratio of  $d1/L$  such that  $0.38 \leq d1/L \leq 0.62$ , which remains within the claimed range of [1f] and [9f]. EX1002, ¶¶149-150.

Therefore, by configuring the conductive light-shielding pattern layer and the drain electrode such that they are spaced apart by a distance along the channel direction in a vertical projection, the  $d1/L$  ratio will decrease (compared to if the entire channel region is shielded), but the resulting  $d1/L$  ratio still lies within the range as recited in claims 1 and 9 from which claims 17 and 18 respectively depend. Accordingly, claims 17 and 18 are obvious in view of Hwang in combination with Godo. EX1002, ¶151.

## VIII. GROUND 3: HWANG AND YAMASHITA

### A. Relationship to Ground 1

Hwang renders obvious the claims as set forth above for Ground 1. In the alternative, to the extent the light-shielding layer limitations are not inherent,



taught, or otherwise rendered obvious to a POSITA by Hwang alone, they would have been rendered obvious over the combination of Hwang and Yamashita.

Ground 3 addresses the alternative, narrower construction of “conductive light-shielding pattern layer.” EX1002, ¶152.

### **B. The Combination**

The combination involves practicing the express teachings in Hwang as set forth in Ground 1, then adding the mental recognition that Hwang’s layer 162/162a would indeed serve the intended design purpose of shielding the semiconductor layer from being exposed to light, to the extent Hwang does not inherently disclose or otherwise render obvious actually performing the light-shielding function. The recognition would have been obvious because it was well known and documented in the art that light can interact with semiconductors and adversely impact electrical performance of TFTs. The problem is exacerbated for transistors in devices like Hwang due to the proximity of integrated light emitting elements (either within the same pixel or in adjacent pixels). *See* Ground 1, Section related to the Knowledge of POSITA regarding light shielding. EX1002, ¶153.

A POSITA would have had a reasonable expectation of success in making the proposed combination because no modification to Hwang’s device is necessary. Such a combination would have merely required express recognition that Hwang’s layer 162/162a is not merely capable of but actually is intended to

perform a light-shielding function, explained below. Further, a POSITA would have recognized relevant similarities between Hwang and Yamashita. For example, both the light-shielding layer 67 in Yamashita and layer 162/162a in Hwang are electrically held at a constant potential. *Compare* EX1006, [0101], EX1004, [0085]-[0086]. *See also* illustrative light scattering paths, to be described further below. EX1002, ¶154.

**C. “a conductive light-shielding pattern layer” ([1f], [9f], 4, 12, 17, 18)**

As shown in Ground 1, [1f], Hwang’s layer 162/162a is the “conductive light-shielding pattern layer” with both conductive and light shielding properties. As designed by Hwang, layer 162/162a is intended to be electrically conductive since it serves as the electrical ground. EX1004, [0083]-[0087]. Although Hwang does not expressly state that an intended purpose of layer 162/162a is to perform a light-shielding function, it would have been obvious to POSITA for it to perform that intended purpose. For example, a POSITA would have recognized that since these devices are not fabricated in complete darkness, once layer 162/162a is formed, light will be incident on the device. Thus, layer 162/162a actually shields underlying structures (including drive transistor Td) from incident light. EX1002, ¶155.

Further, Hwang discloses that after layer 162/162a is formed, insulating layer 164 (made with optically transparent SiO<sub>2</sub> glass) is deposited and patterned

thereon. EX1004, [0088]. Patterning layer 164 involves photolithography that exposes the device to light. Thus, layer 162/162a actually shields Td from light during that fabrication step as well. EX1002, ¶156.

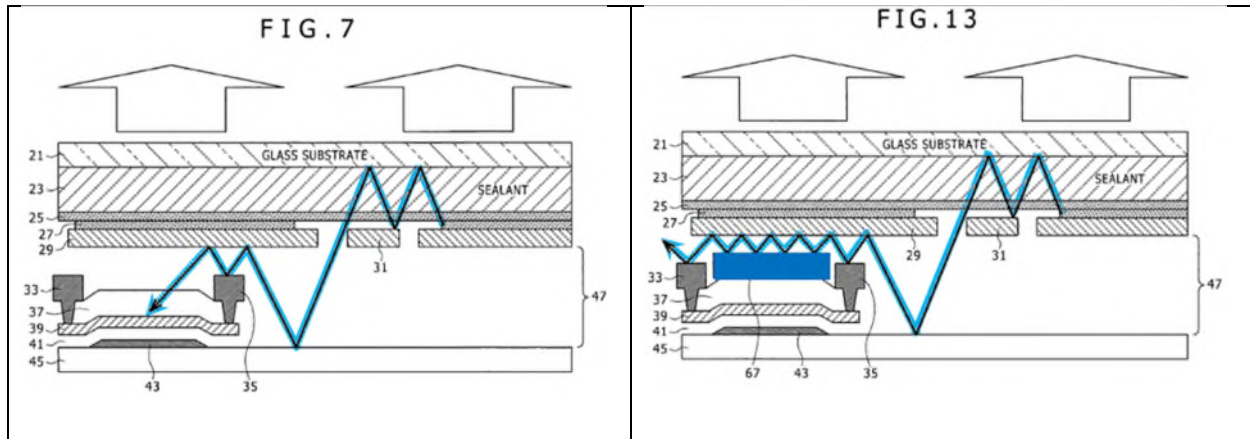
Moreover, Yamashita discloses that during operation, light generated by the LED's in adjacent pixels can be scattered internally enter channel region of TFTs integrated into the same chip and adversely impact device performance. EX1006, [0037]. *See* discussion of Yamashita in Ground 1, B (Knowledge of a POSITA). Figure 7 of Yamashita is an exemplary illustration<sup>3</sup> showing a “light ray” whereby light can be scattered into the channel region of a TFT. EX1006, Fig. 7, [0035]-[0037]. Yamashita teaches using a patterned metal layer (67) to shield the transistor from the scattered light. EX1006, [0095]-[0099]; compare Figs. 7 and 13

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<sup>3</sup> A POSITA would have recognized that the illustrated light path is merely exemplary, and additional pathways exist for light to scatter into the channel region of the TFT. Further, while different devices may have arrangements of the reflective layers, the different arrangements of the reflective layers would merely lead to different pathways whereby light can reach the TFT channel regions. Thus, Fig. 7 of Yamashita illustrates the more general teachings that motivate the need for shielding the transistor from scattered light. EX1002, ¶157 n.6.

(annotations added to show scattered light with and without the light shield layer

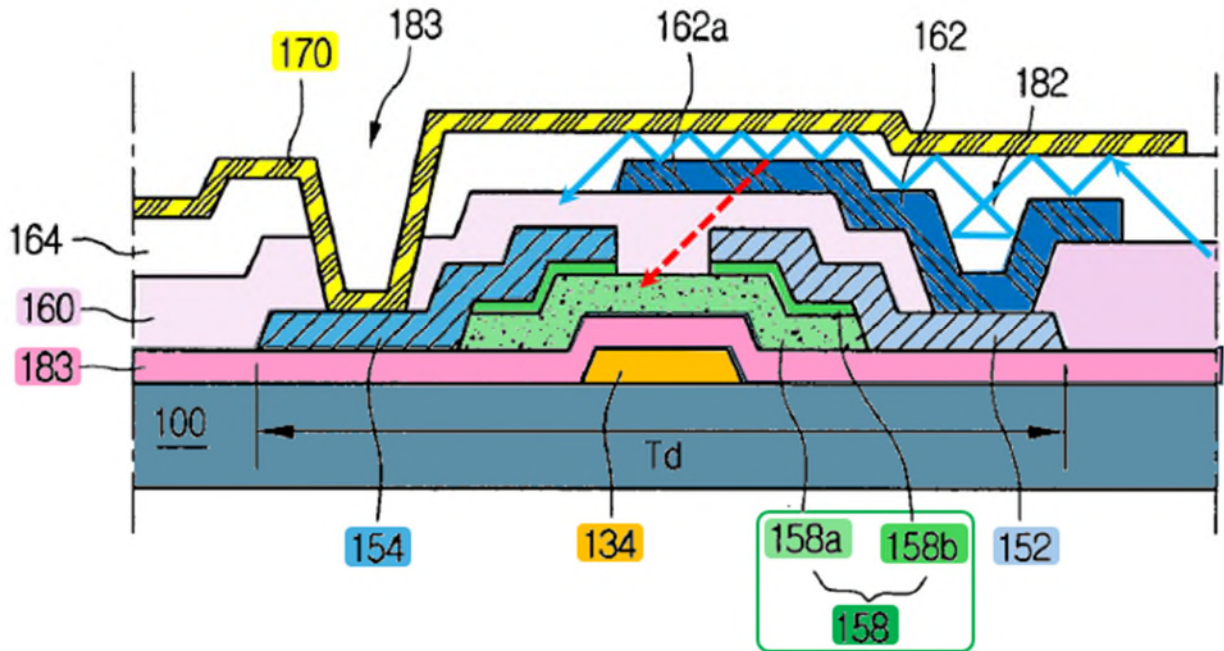
67).



See also KR100853543 (EX1010, Abstract, <9>, <16>, <38>, <39>) disclosing the problem of light generated from an adjacent pixel adversely impacting a drive TFT, as discussed in Section VI.B (Knowledge of POSITA regarding light shielding). EX1002, ¶157.

Thus, based on the teachings in Yamashita, a POSITA would have recognized that light generated by Hwang's LEDs can be internally scattered and enter the channel region of transistor Td, in the absence of metal layer 162/162a. This is illustrated using two versions of Fig. 6d reproduced below. The first version shows an exemplary optical pathway, with light (in light blue) originating from the right side then scattering within the structure (including by reflecting off lower electrode 170, similar to the reflection off electrode 29 in the configuration as disclosed in Yamashita) and reaching the channel region of Td (in red).





EX1004, Fig. 6d (annotations added) with red dotted arrow showing one exemplary light ray that is shielded from the channel region. Accordingly, in view of the Yamashita's teachings, a POSITA would have recognized Hwang's layer 162/162a as designed would serve the additional intended purpose of actually shielding light from the channel region of transistor Td (*i.e.*, part of the channel layer) and meet the limitation [1f]/[9f] even under the alternative construction.

EX1002, ¶159.

Regarding dependent claims 4, 12, 17, 18, the antecedent basis for the conductive light-shielding pattern layer recited therein comes from limitation [1f] or [9f]. Therefore, layer 162/162a meets the limitations recited in those dependent claims for the same reasons set forth above. Dependent claims 6 and 14 are not impacted by the alternative construction for "conductive light-shielding pattern

layer” and therefore the limitations recited therein are disclosed by Hwang or rendered obvious for the same reasons as set forth in Ground 1. EX1002, ¶160.

## **IX. GROUND 4: HWANG, GODO AND YAMASHITA**

### **A. Relationship to Grounds 1-3**

Hwang renders obvious the claims as set forth above for Ground 1. In the alternative, to the extent the dimensional or light-shielding layer limitations are not taught or rendered obvious to a POSITA by Hwang alone, they would have been rendered obvious over the combination of Hwang and Godo, or Hwang and Yamashita, as set forth for Grounds 2 and 3 respectively. Ground 4 addresses an additional alternative where both the light-shielding layer limitations (under the narrower construction) and the dimensional limitations are not taught or rendered obvious to a POSITA by Hwang alone. Each of the challenged claims would have been obvious over the combination of Hwang in view of Godo and Yamashita. EX1002, ¶161.

### **B. The Combination**

The combination of Hwang and Godo is addressed in Ground 2, Section B, and the combination of Hwang and Yamashita is addressed in Ground 3, Section B. For the reasons set forth in Ground 3, Section B, adding Yamashita to the combination of Hwang and Godo would have required no modification to Hwang’s layer 162/162a other than the designer intend that layer 162/162a perform the light-shielding function. Thus, a POSITA would have been motivated to combine

these references, and would have had a reasonable expectation of success for the same reasons set forth in Ground 2, Section B and Ground 3, Section B. EX1002, ¶162.

**C. “a conductive light-shielding pattern layer... the conductive light-shielding pattern layer and the channel layer have an overlapping length  $d_1$ , and  $0.3 \leq d_1/L \leq 0.85$ ” ([1f], [9f], 4, 12, 17, 18)**

See discussion in Ground 3, Section C discussing the “conductive light-shielding pattern layer” limitation and Ground 2, Section C discussing the  $d_1/L$  dimensional ratio limitation and Ground 2, Section D discussing the “spaced by a distance...” limitation. Therefore, claims 1, 4, 6, 9, 12, 14, 17 and 18 are rendered obvious by Hwang in view of Godo for the reasons set forth therein. EX1002, ¶163.

**X. DISCRETIONARY DENIAL IS NOT WARRANTED**

**A. 35 U.S.C. § 314(a) Analysis**

The *Fintiv* factors (enumerated below) weigh against discretionary denial. IPR2020-00019, Paper 11, 5-6 (PTAB Mar. 20, 2020) (precedential). The “Interim Procedure for Discretionary Denials in AIA Post-Grant Proceedings with Parallel District Court Litigation” dated June 21, 2022 (“Interim Guidance”) and recent board decisions applying these factors confirm discretionary denial is not warranted here.



### **1. Stay**

Neither party has requested a stay in the related litigation between the parties. At worst, this factor is neutral because the Board “will not attempt to predict” how the district court will proceed if a stay has not been requested by either party. *Sand Revolution II, LLC v. Continental Intermodal Group – Trucking LLC*, IPR2019-01393, Paper 24 at 7 (June 16, 2020) (informative).

### **2. Trial Date**

The deadline for a Final Written Decision will be in early August 2026. Jury selection for a trial in this matter has been set for May 4, 2026. *See* EX1018 (Docket Control Order). There are currently 11 trials set for the same date as this matter’s jury trial, and therefore it is likely that the District Court vacates this trial date and trial will occur around the same time or slightly after a Final Written decision is rendered. *See* EX1019 (Docket Report). Thus, at the time of this Petition, this factor is either neutral or weighs slightly in favor of institution.

### **3. Parallel Proceeding**

Petitioner is filing this IPR when only Plaintiff’s initial infringement contentions have been served. EX1017, Initial Infringement Contentions for U.S. Patent No. 8,604,471 (Initial Infringement Contentions). By the time an institution decision is rendered (in early August 2025), *Markman* briefing will have not begun (opening brief due September 29, 2025) the *Markman* hearing is not scheduled to occur until November 10, 2025. *See* EX1018. Further, fact discovery will not close

until December 15, 2025, many months after institution. *Id.* Accordingly, given parties' investment in the parallel proceeding is not extensive, this factor weighs in favor of institution.

#### **4. Issue Overlap**

This Petition challenges claims 1, 4, 6, 9, 12, 14, 17, 18 while the litigation currently only involves claims 1 and 17. *See* EX1017. The challenged claims in this proceeding include additional subject matter including independent claim 9 (and multiple additional dependent claims), which includes upper and lower electrodes not included in claims 1 and 17. Seventy-five percent of the subject matter challenged in this petition is not at issue in the underlying litigation. Thus, this factor weighs strongly in favor of institution.

#### **5. Same Party**

Because Petitioners and the PO are the parties in the Litigation, and because this Board is likely to reach the merits around the same time as the district court, this factor weighs slightly against discretionary denial or is neutral. *See NVIDIA Corp. v. Invensas Corp.*, IPR2020-00603, Paper 11, at 23 (finding this factor weighs against discretionary denial where district court trial and IPR final written decision are expected "around the same time").

#### **6. Other Considerations**

Other considerations weigh strongly against a discretionary denial. The Challenged Claims are clearly invalid, Petitioners have not previously challenged

any related patents based on the references relied upon in this petition, and the 471 patent has never been challenged in a post-issuance proceeding.

Even if the Board were to determine that *Fintiv* factors on balance weigh in favor of denial, institution should nonetheless be granted because this Petition satisfies the compelling merits standards. Interim Guidance at 4; *Vizio, Inc. v. Maxell, Ltd.*, IPR2022-01458, Paper 8, at 62.

**B. 35 U.S.C. § 325(b) Analysis**

Applying the two-part framework discussed in *Advanced Bionics, LLC v. Med-El Elektromedizinische Gerate GMBH*, IPR2019-01469, Pap. 6, \*8-9, the Board should not exercise its §325(d) discretion to deny institution. Neither of the challenges are substantially the same as those considered during prosecution. The claims were allowed based on the addition of the limitation that the layer not cover the drain, which is clearly disclosed in Hwang as shown above. To the extent that the challenges herein are found to be based on prior art that is the same as or cumulative to prior art considered by the examiner during prosecution, the examiner has made a clear error in allowing the claims over such prior art. This is at least because the challenges in this Petition satisfy the compelling merits standard, and allowing the claims over such prior art is therefore clear error.

**XI. MANDATORY NOTICES UNDER 37 C.F.R. §§ 42.8(B)(1)-(4)**

**A. Real Party-In-Interest**

BOE Technology Group Co., LTD is the real party-in-interest.

**B. Related Matters**

The 471 patent is subject to the following actions: *Optronic Sciences LLC v. BOE Technology Group Co., LTD*, 2:24-cv-00577 (EDTX).

**C. Lead and Backup Counsel**

Lead Counsel	Backup Counsel
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**D. Service Information**

Please address correspondence to counsel at the addresses above. Petitioner consents to electronic service to: [dla-boe-optronicsciences-IPR@us.dlapiper.com](mailto:dla-boe-optronicsciences-IPR@us.dlapiper.com) and the email addresses listed above.

**E. Proof of Service on the Patent Owner**

In accordance with 37 C.F.R. §§42.6(e) and 42.105, as identified in the attached Certificate of Service, a copy of this Petition in its entirety is being served electronically (by agreement) on counsel for Patent Owner in the District Court Litigation.

**F. Power of Attorney**

Powers of attorney are being filed with designation of counsel in accordance with 37 C.F.R. § 41.10(b).

**G. Standing**

In accordance with 37 C.F.R. §42.104(a), Petitioner certifies that the 471 patent is available for *inter partes* review and that Petitioner is not barred or estopped from requesting an *inter partes* review challenging the patent claims on the grounds identified in this Petition.

**H. Fees**

The undersigned authorizes the Director to charge the fee specified by 37 C.F.R. § 42.15(a) and any additional fees that might be due in connection with this Petition to Deposit Account No. 503266.

**XII. CONCLUSION**

All Challenged Claims of the 471 patent should be found unpatentable for the reasons discussed in this Petition.

Date: February 19, 2025

Respectfully submitted,

/Brian Erickson/

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*Attorney for Petitioner, BOE  
Technology Group Co., LTD.*

### **CERTIFICATE OF WORD COUNT**

Pursuant to 37 C.F.R. § 42.24(d), Petitioner certifies that this petition includes 12,055 words, as measured by Microsoft Word, exclusive of the table of contents, mandatory notices under § 42.8, certificates of service, word count, claim listing, and exhibits.

Date: February 19, 2025

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### **CERTIFICATE OF SERVICE**

The undersigned certifies pursuant to 37 C.F.R. §§ 42.6(e) and 42.105 that on February 19, 2025, a true and correct copy of the Petition for *Inter Partes*

Review of U.S. Patent No. 8,604,471 was served by emailing a copy of same (by agreement) to the following attorneys for the Patent Owner:

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Respectfully submitted,

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